



# Roadmap for Copper Sintering - Next Interconnect for Power Electronic Module Packaging

Semicon, Vitsco, Siemens



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# Technische Hochschule Ingolstadt

## Introduction

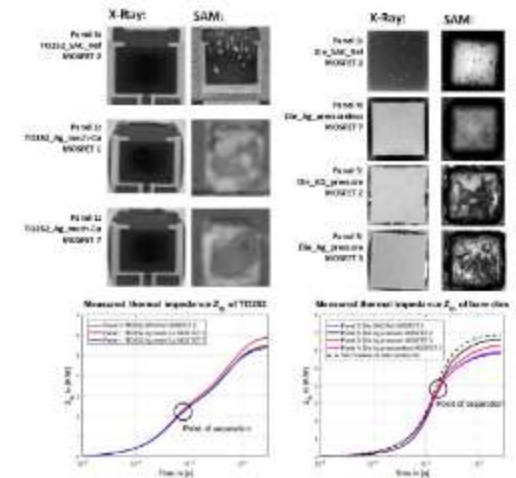
### ■ Microelectronics packaging research group of the Institute of Innovative Mobility at Technische Hochschule Ingolstadt (THI)

- Process development of fluxfree soldering and sintering
- Paste development (Fluxfree solder pastes, copper sinter paste, copper inks)
- Reliability and lifetime testing
- Test equipment development, e.g. Transient thermal analysis (TTA)
- Modelling (Finite Element and Machine Learning)

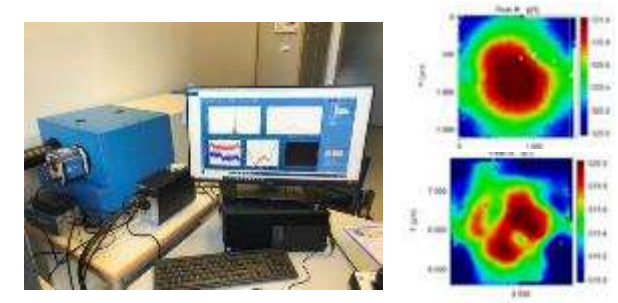
### ■ Copper Sinter development projects started 2017

### ■ Since 2019 research cooperation with Schlenk (metal pigments and copper foils)

### ■ 2022 CuNex was founded as Joint Venture between researchers from THI (CEO Krishna Bhogaraju) and Schlenk



Detection of crack formation by TTA and Scanning Acoustic Microscopy (SAM)



RAMAN Strain measurement in semiconductor

# Content



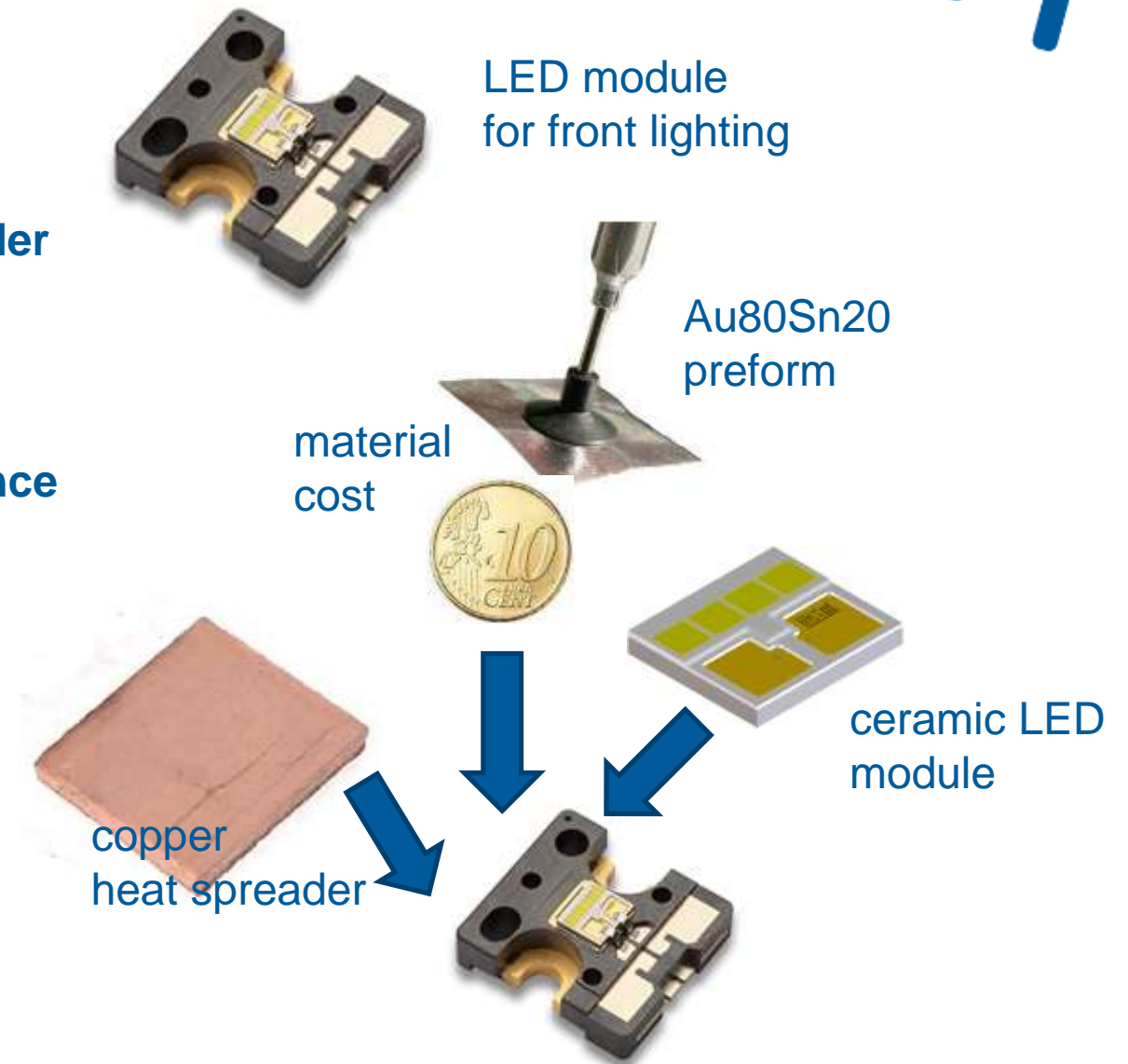
- **Introduction**
  - Sintering
  - Market
- **Copper Pastes and Sinter Processes**
- **Copper Paste Development Status @ THI**
- **Roadmap THI/CuNex**

# Personal Motivation from 2008 @ Philips/Lumileds



## Introduction

- For heat management of high power LEDs ceramic carrier is mounted on copper heat spreader
- Due to thermomechanical mismatch of copper and ceramic large thermomechanical stress
- AuSn used as solder with high fatigue resistance (yield strength 200MPa)
- Silver Sintering lower reliability (in that time)
- Replacing AuSn solder by copper paste
- Process requirement:
  - Temperature < 320°C
  - Time < 30s



# Motivation



## Introduction

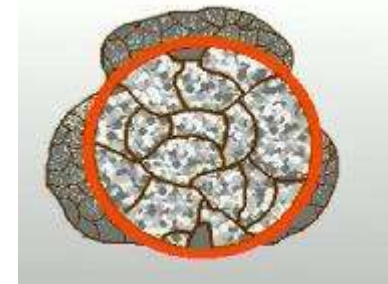
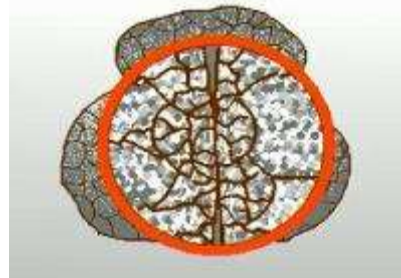
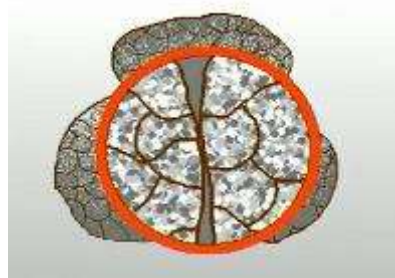
### ■ Sintering – Well known technology for primary shaping

Metal Powder

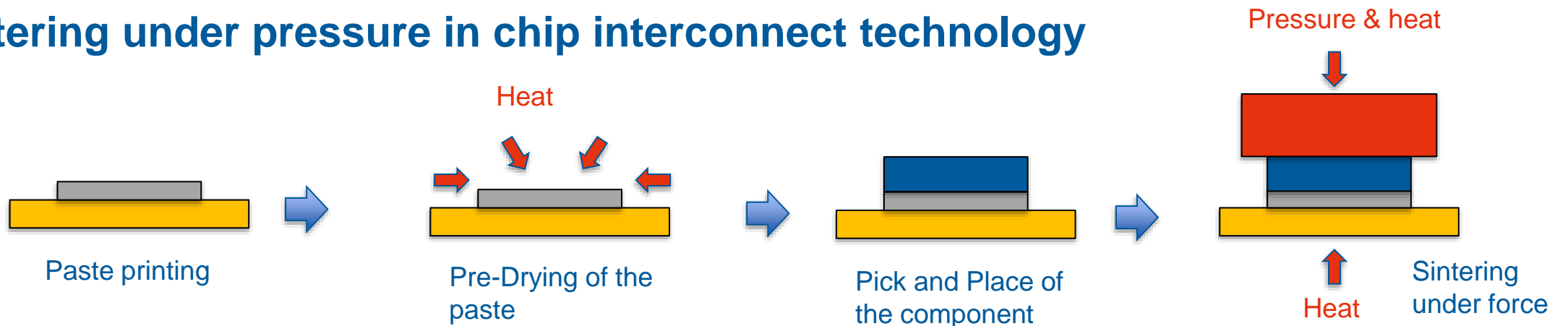
Force: Deformation →  
Contact area increased

Temperature: Diffusion  
→ Recrystallization

Interconnect



### Sintering under pressure in chip interconnect technology

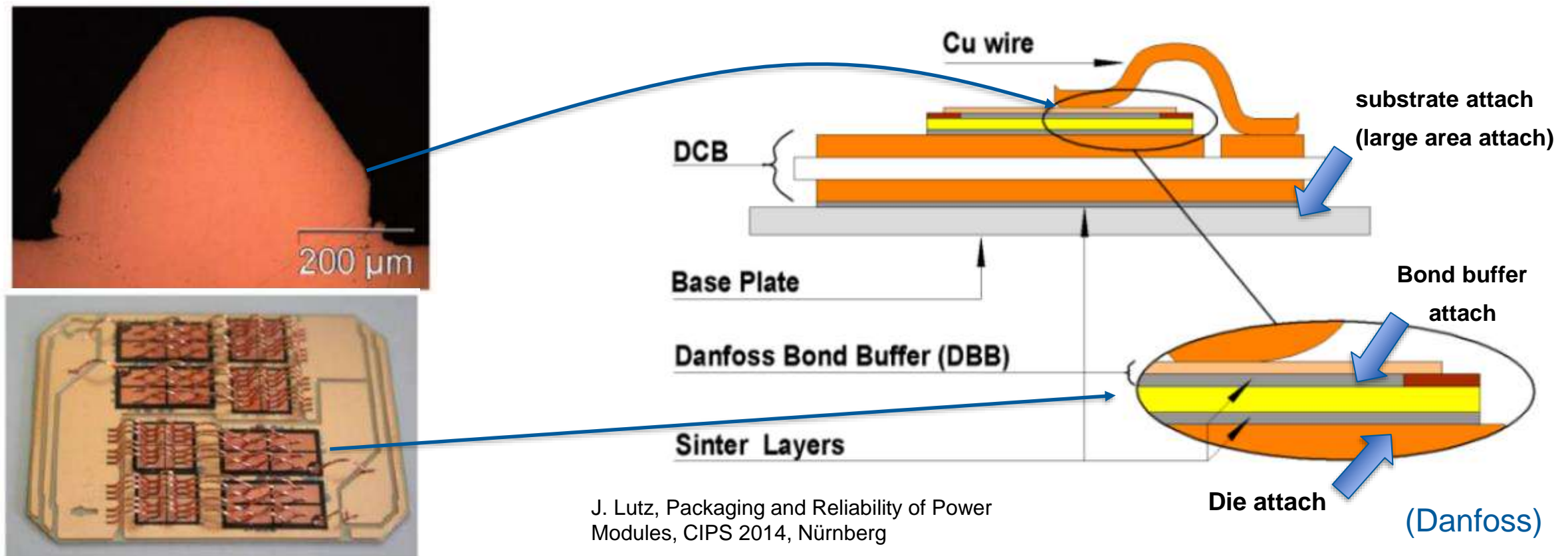


# Standard Modul

## Introduction



- Example design of Power electronic module with three sintered interconnects



J. Lutz, Packaging and Reliability of Power Modules, CIPS 2014, Nürnberg

# Power Module Packaging Market



## Introduction



- The die- and substrate-attach material industry is expected to grow significantly in size

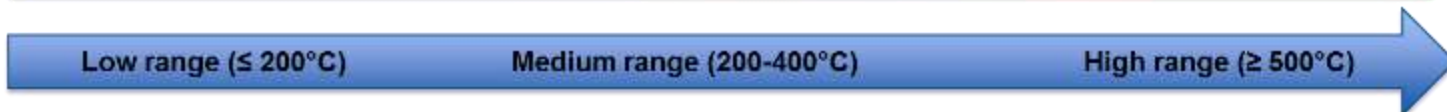
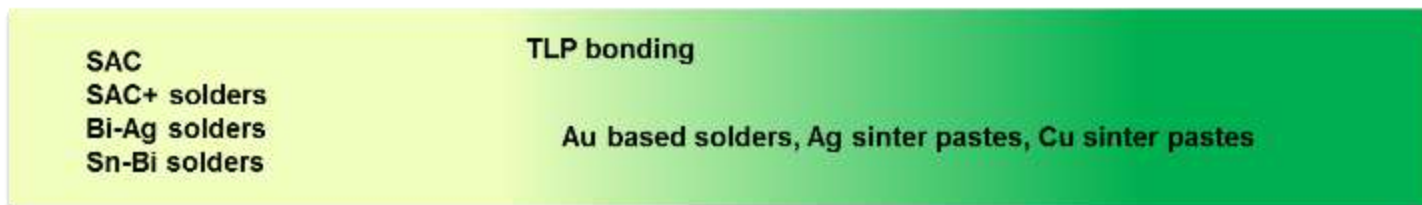
- Driving forces

- Rapid pace of electrification in the automotive industry (vehicles and charging infrastructure)
- Renewable power sources are major driving forces.

- New cost-effective die-attach materials are needed that are as reliable as Ag and sustainable



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# Comparison Copper and Silver



## Introduction

■ **Cu offers both a substantial cost advantage over Ag and comparable mechanical and thermal properties.**

■ **Challenges**

- Oxidation of Cu particles
- Higher sintering temperature

Primary silver production requires significant more energy



Property (unit)	Ag	Cu
Cost (\$/kg)	500	5
Abundance in earth's crust (ppm)	0,08	50
Thermal expansion ( $\mu\text{m}/\text{mK}$ )	429	401
Elastic modulus (GPa)	83	120
Bulk modulus (GPa)	100	140
thermal conductivity (W/mK)	429	400
Melting point ( $^{\circ}\text{C}$ )	962	1085
Embodied Energy (MJ/kg)	1500	100



# Status Silver and Copper Sintering

*Paste and Processes*



- Ag sintering in electronics started in the 1990th with the patents and research work from H. Schwarzbauer in 1989
- Ag sintering under pressure was introduced in manufacturing and can be considered as a mature technology
- However, standardization in the process compared to SMD soldering is very low
- Pressureless, Ag sintering based on nanoparticles followed when nano powder got available and is now in productions since more than 5 years
- Intense research work was ongoing in the last five years on copper sintering
- Paste is available since roughly three years (engineering materials)
- Nowadays, copper sintering in the evaluation and design-in for new product generations

# Copper Sinter Materials

## Paste and Processes

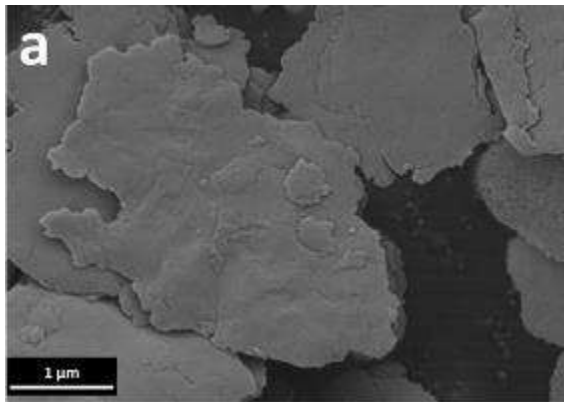


### Similar to silver particles

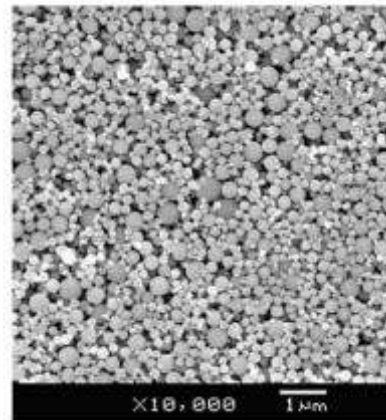
- Micro particles: flakes or spheres
- Nano particles
- Metal salts (particle free)



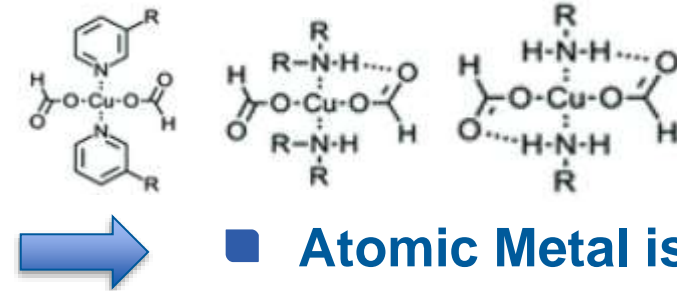
copper formate  $\text{Cu}(\text{HCOO})_2$ ,  
copper acetate  $\text{Cu}(\text{CH}_3\text{COO})_2$ ,  
copper oleate  $\text{Cu}(\text{C}_{17}\text{H}_{33}\text{COO})_2$



Copper Flakes (200nm thickness)



Nano particle



- Atomic Metal is produced and forms particles

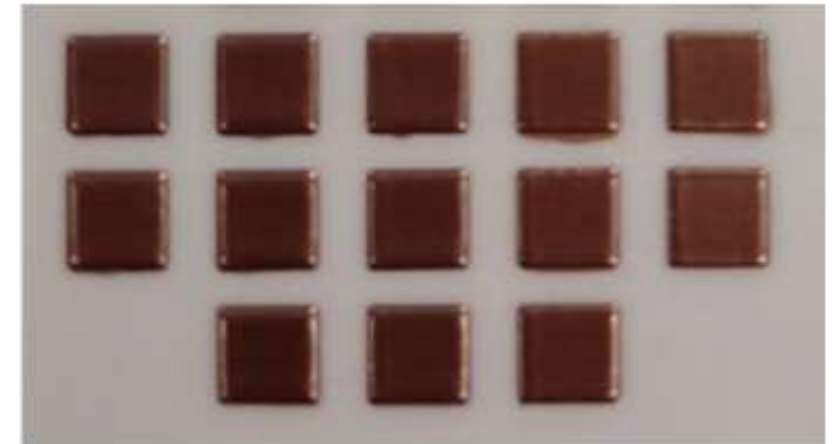
- Metal particles need surface protection/coating to protect surface, e.g. oxidation, and hinder agglomeration and sintering of particles before the interconnection process

# Sinter Process

## *Paste and Processes*



- **Binder contains composition to**
  - provide printability
    - Mixture low and high boiling fluids
  - realize activation at defined sinter temperature
    - particle surfaces
    - sinter pads
  - reducing agents
  - prohibit agglomeration
  - prohibit bleed out
- **Binder evaporates residual free at sinter temperature**
- **Required pot life**



**Schlenk copper paste (THI / CuNex inside)**

# Sinter Process Sequence



## Paste and Processes

### ■ Paste /Material application

- Stencil and screen printing
- Dispensing

### ■ Predrying

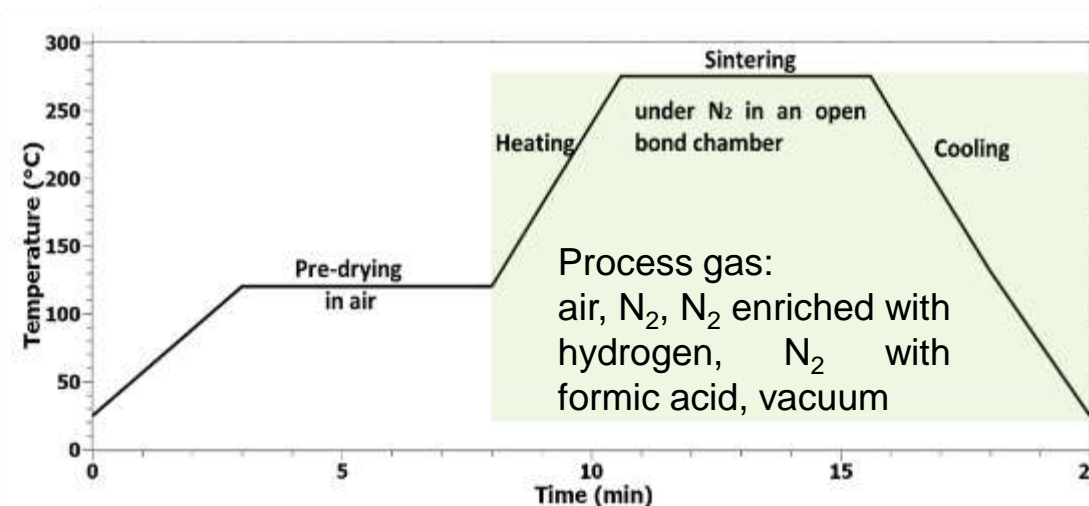
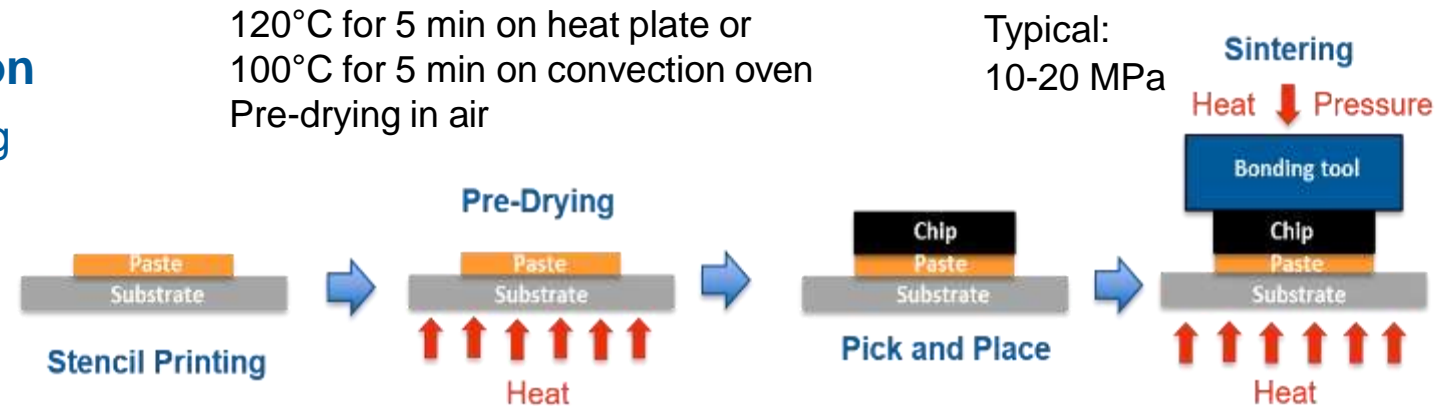
- paste is fully dry
- paste still slightly sticky

### ■ Pick and Place (P&P)

- applying tacking agent and P&P
- prebonding with hot tool and force
- P&P still sticky paste

### ■ Sintering

- Closed or open bond chamber (residual oxygen)
- Stamp tool and press technology



■ Processes are presently still considered as IP.

■ When will be a standardization for the process ?

■ It would be better soon!

# Copper Sinter Paste – the commercial landscape



*Copper Paste and Processes*

Most important (but non exhaustive) list of suppliers ... more are coming.

Company	Particles size	Sintering time (min)	Sintering temperature (°C)	Sintering pressure (MPa)	Controlled atmosphere	Shear strength (MPa)
Heraeus	Micro Cu	5	325	20	Yes	30
Indium Corporation	Nano Cu	15	240	0	Yes	17
Showa Denko	Nano Cu	5	280	9	Yes	80
Mitsui Mining	Nano Cu	60	200	0	Yes	60
Kuprion	Nano Cu	<8	200-230	NA	NA	NA
CuNex P1	Micro Cu	5	275	10	No	60
CuNex P2	Cu salt	5	250	20	No	100

Status: partly commercial product - partly available engineering sample

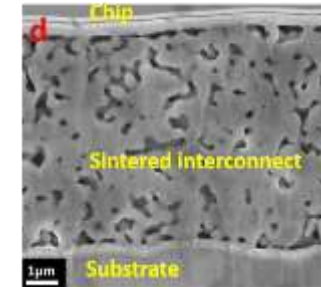


# Copper Paste Building Block System

Copper Paste Development @ THI

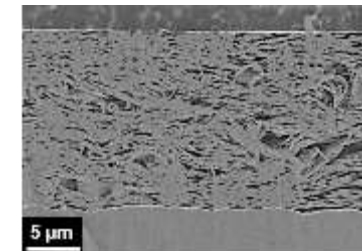
## Cu salt based sinter paste

Suitable for bondline thickness requirements  $< 10 \mu\text{m}$  and bulk-like sintered interconnects.



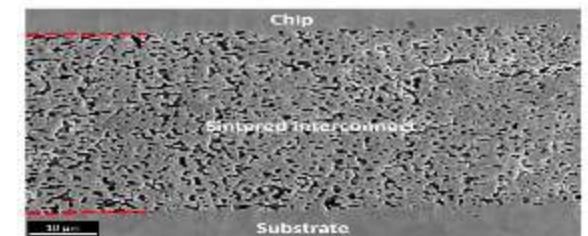
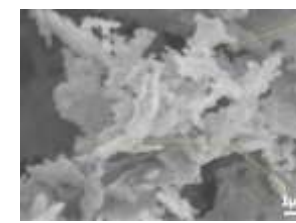
## Cu flake based sinter paste

Stacked Cu flakes with pores oriented parallel to the interconnect. Easily deformable flakes to compensate surface roughness & near “zero” porosity under high pressure sintering



## Surface modified brass flakes based sinter paste

Tunable porosity & young's modulus for application specific requirements

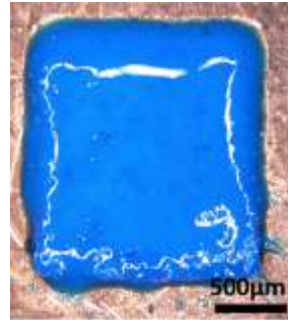


# Copper Salt Paste

Copper Paste Development @ THI

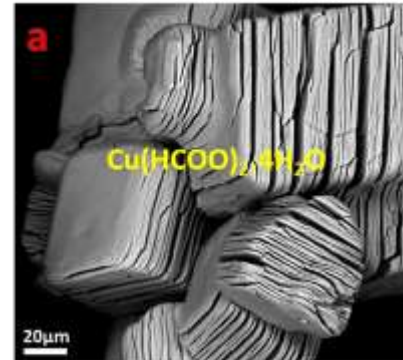


## Cu salt based sinter paste



- Sinter paste based on Cu(II) formate tetrahydrate.
- Cu nanoparticles generated in-situ during the sintering process by thermal decomposition of Cu(II) formate.
- Suitable for bondline thickness requirements < 10 µm and bulk-like sintered interconnect.
- By adding complex builders (e.g. amino-2-propanol and hexylamine) the decomposition temperature can be reduced

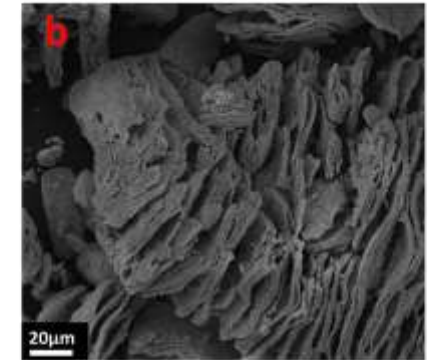
Commercially procured  $\text{Cu}(\text{HCOO})_2 \cdot 4\text{H}_2\text{O}$



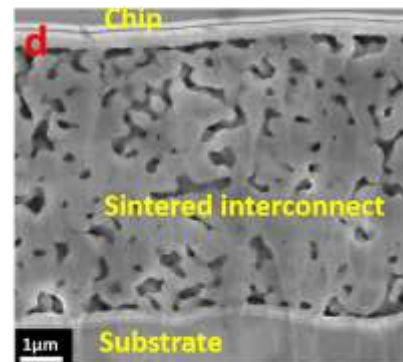
250°C for 10 min  
under nitrogen

under  $\text{N}_2$

Intermediate stage of thermal decomposition



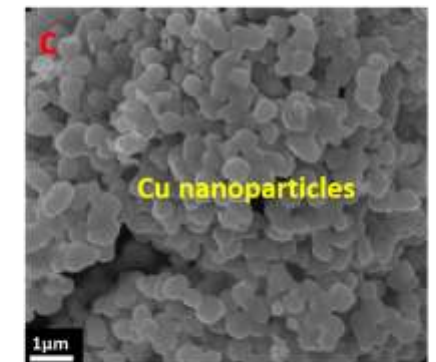
at 250°C for 30 min  
under  $\text{N}_2$



Sintered interconnect

275°C 5min 10 MPa  
Nitrogen in open bond  
chamber

Under 20MPa and  $\text{N}_2$



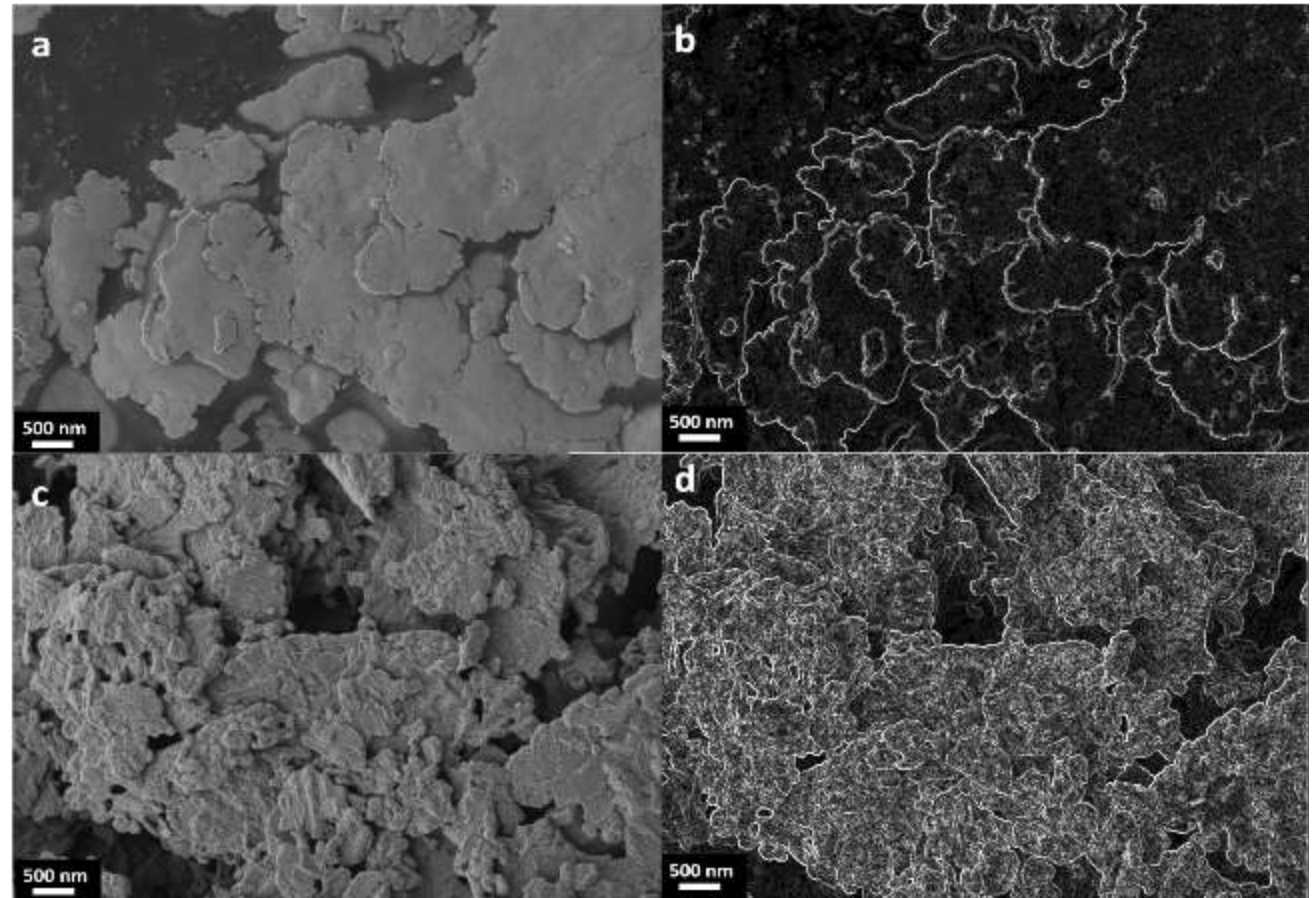
Complete decomposition of  $\text{Cu}(\text{HCOO})_2 \cdot 4\text{H}_2\text{O}$ ;  
development of Cu nano particles

# Nanostructured Brass Flakes



*Copper Paste Development @ THI*

- As low cost initial ball grinded brass flakes (30%Zn and 7%Zn) were used as initial material (below 100€/kg)
- Etching with 12 M HCl for 4 hours while stirring at 600rpm at room temperature
- SEM images of the Cu-alloy powder (a) before etching and (c) after etching. Surface and edge detection by open source imagej software (b) before etching and (d) after etching.



Cu7%Zn after 4h etching



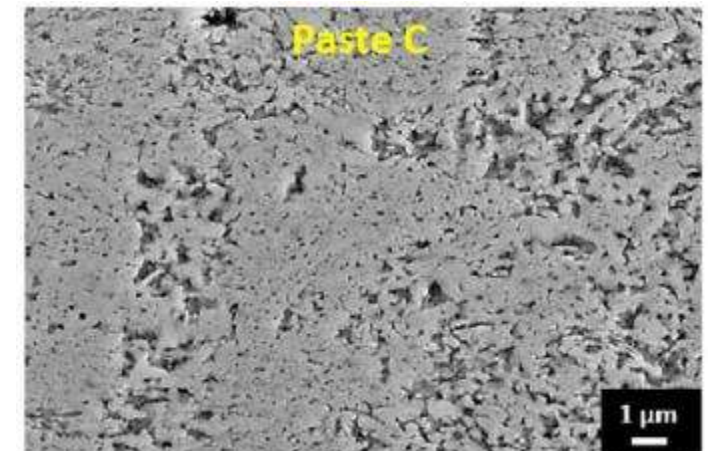
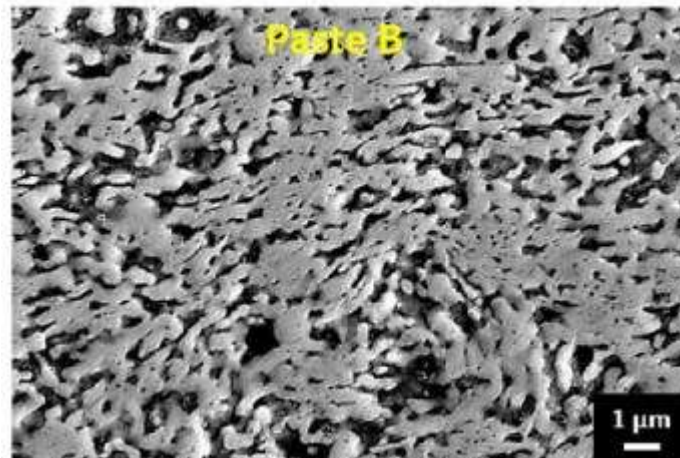
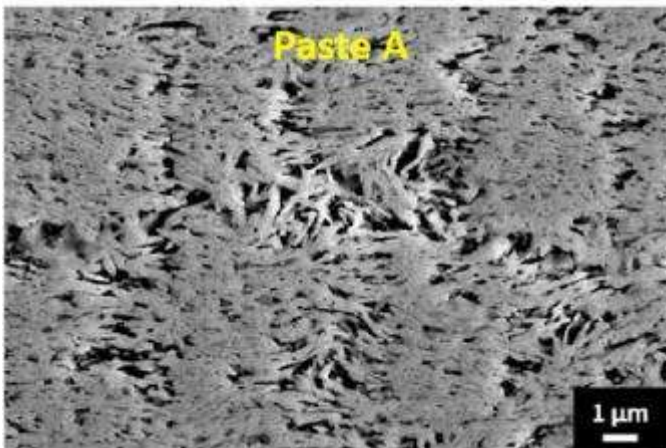
# Dependence initial Zn Content of Brass Flakes



Copper Paste Development @ THI

- SEM images of the microstructure of the pastes A, B, and C sintered at 275 °C for 5 min under 10 MPa.
- Porosity can be adjusted by etching

sinter paste	Zn concentration (wt %) in flakes				paste formulation (wt %)
	original flakes	after etching			
		1 M	6 M	12 M	binder to flakes
paste A	3.0	1.1	0.9	0.7	65:35
paste B	7.7	4.1	3.8	3.0	63:37
paste C	25.6	15.4	13.9	6.4	64:36
reference Cu	na				60:40

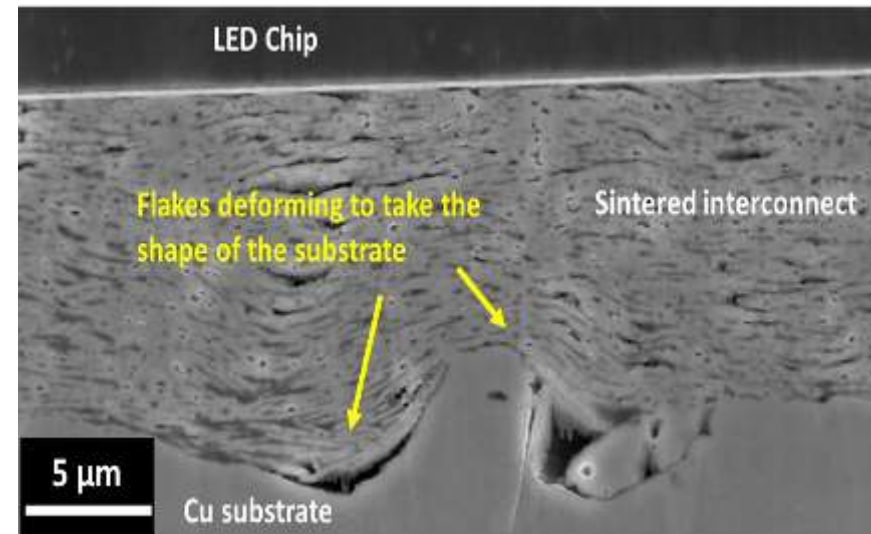
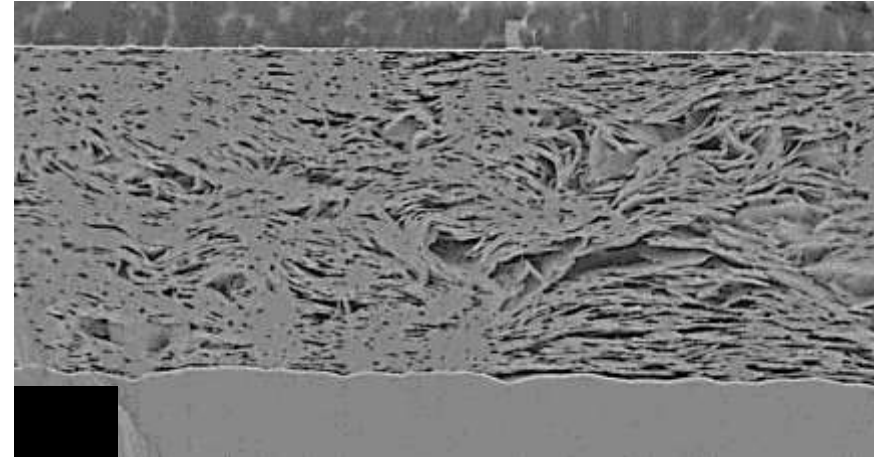


# Stacked Copper Flakes

*Copper Paste Development @ THI*

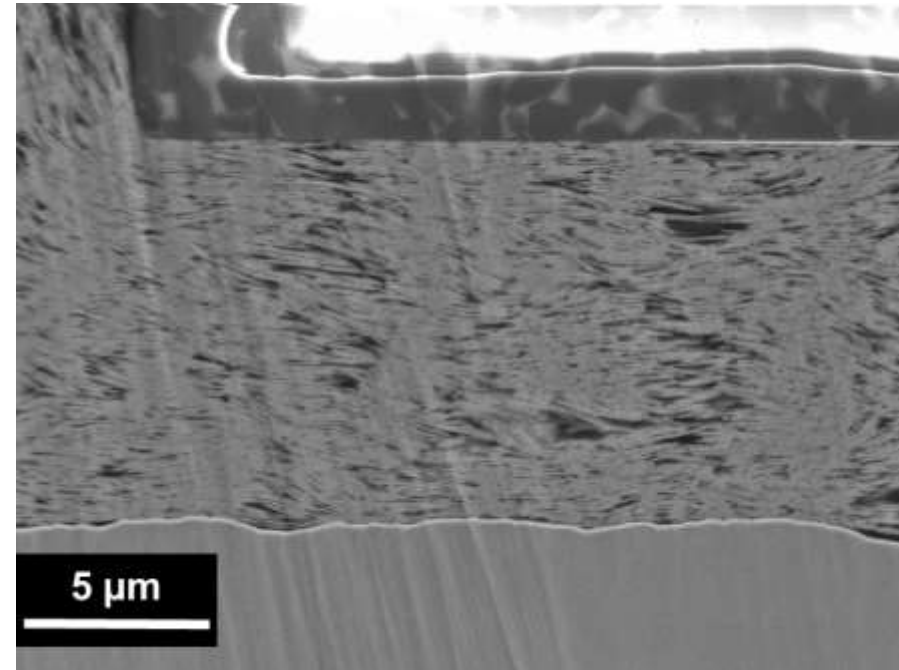
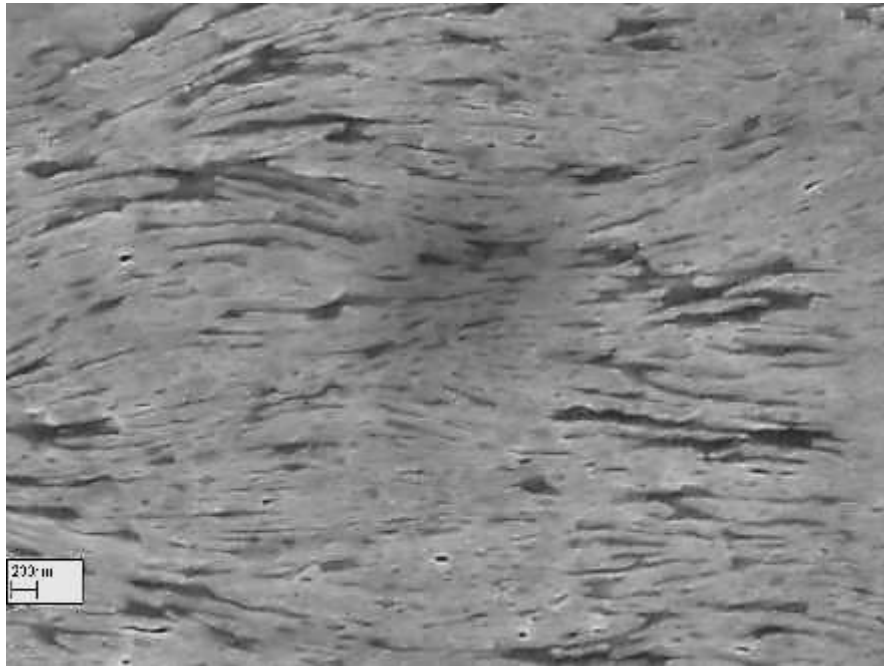


- Sintering @ 275°C and 20 MPa bonding pressure.
- Porosity < 20%
- Shear strength > 50 MPa.
- Proven performance of >1 million power cycles at  $\Delta T 135K$
- Suitable for die-attach bonding and substrate attach (large area bonding)
  
- Capability of the flakes to bend along surface roughness/irregularities



# Stacked Copper Flakes

*Copper Paste Development @ THI*



- Flakes stack over each other and show readiness to sinter together.
- Interconnect is dominated by long, thin interconnected pores.
- Very good sinterability to chip and substrate metallization and edges.

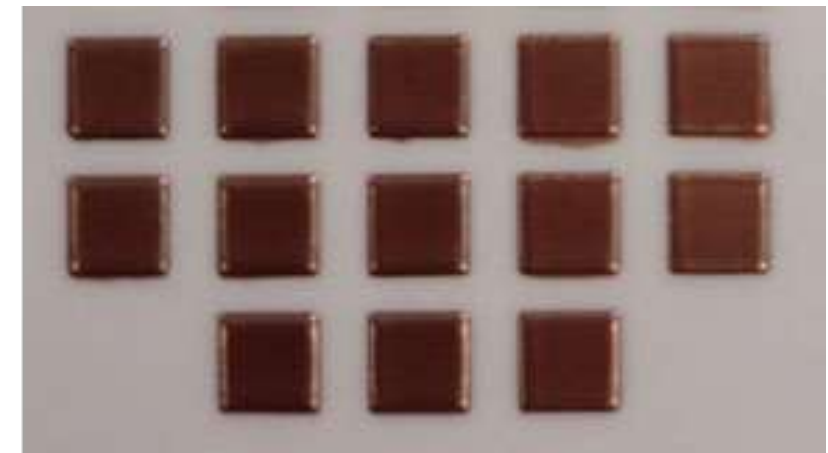
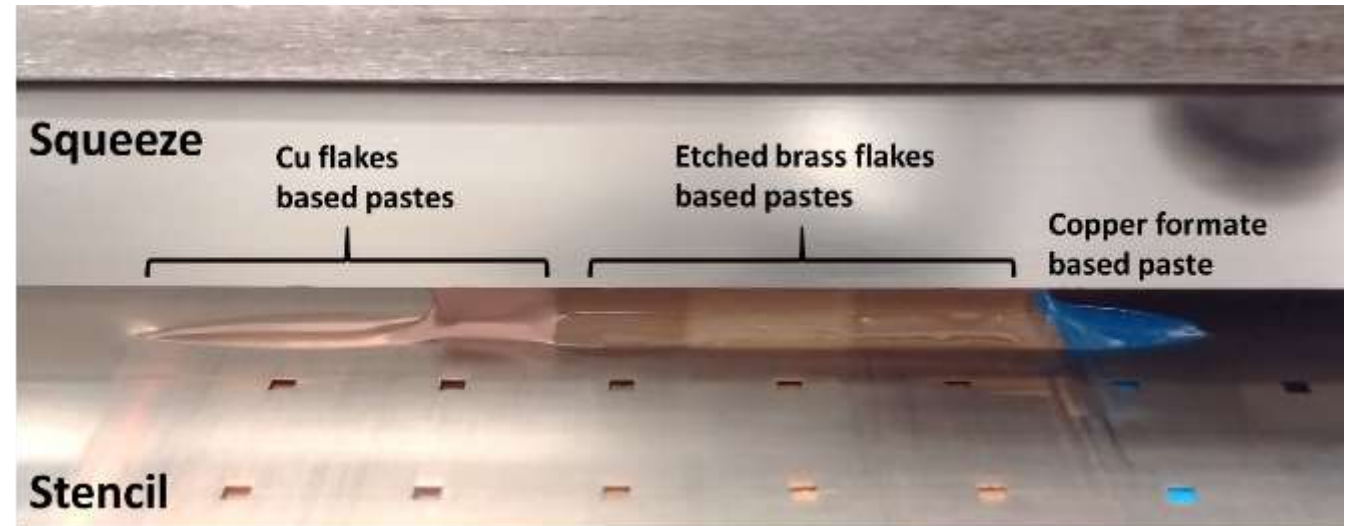
# Stencil Printing Capabilities & Parameters



*Copper Paste Development @ THI*

- Paste shows very good workability & stencil/screen printing capabilities.
- Easy separation from the stencil and squeeze & very good form adherence.
- Storage at room temperature for 6 months.
- Mixing by a planetary rotary mixer for 5 min at 500 rpm before usage.
- Stencil printing

Print results: Semi-automatic stencil printer (PBT, Go3v) with a motorized double blade squeegee and a stencil thickness of 75  $\mu\text{m}$ . Squeegee speed was 13 mm/s, squeegee pressure 20 N and the stencil separation 2.3 mm/s.



# Status: THI Copper Paste Compared to Silver Paste

Copper Paste Development @ THI

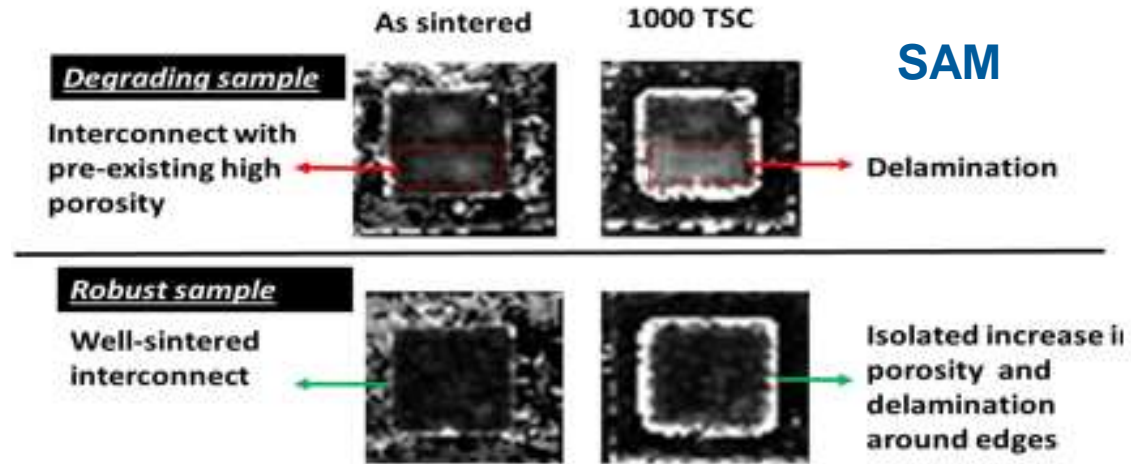


*Where do we stand compared to commercial micro scale Ag sinter pastes?*

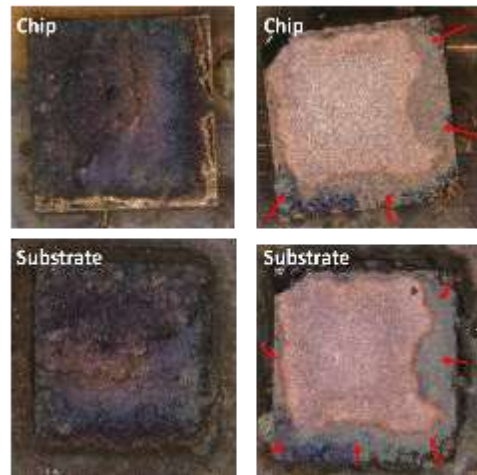
Parameters	Cu sintering	Ag sintering (commercial micro scales flakes based sinter paste)
Temperature (°C)	250-275	230-280
Bonding pressure (MPa)	5-20	10-30
Sintering time (min)	1-5	1-5
Shear strength (MPa)	30-120	30-75
Sintering atmosphere	Nitrogen/Open bond chamber	Air/Nitrogen
Metallization compatibility	Cu, Ag, Au	(Cu), Ag, Au

# Reliability Under High Stress Condition

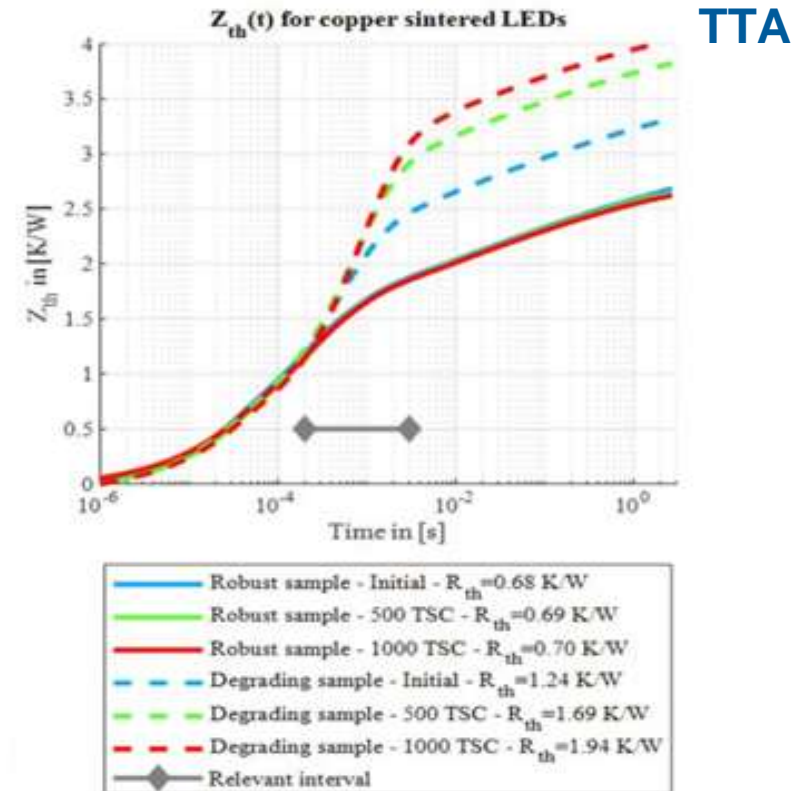
Copper Paste Development @ THI



Oxidized interconnect



Oxidation is limited to outer edges due to low porosity of the interconnect



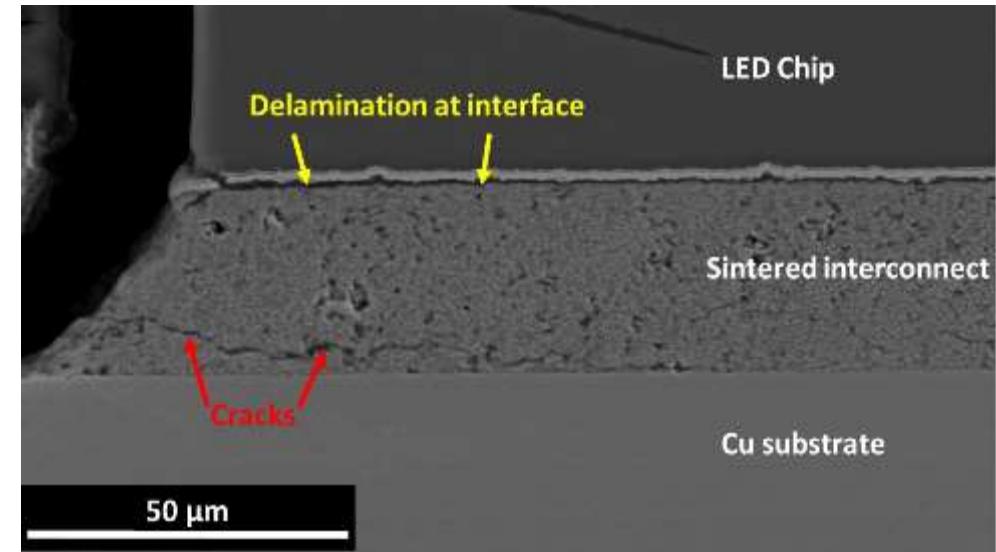
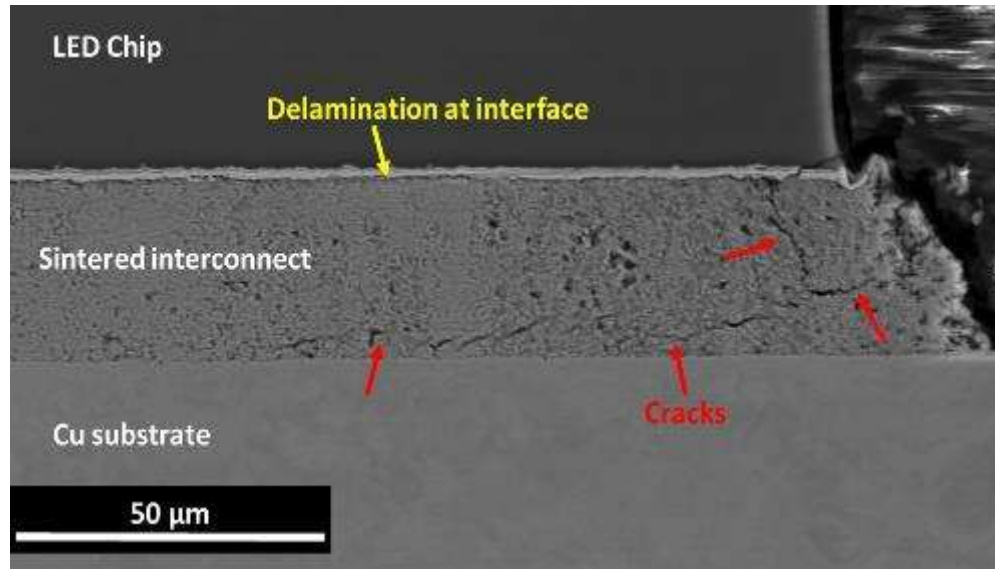
- Measuring degradation by transient thermal impedance and Acoustic Microscopy (SAM)

# Crack Formation at the Corner



*Copper Paste Development @ THI*

- 1mm Silicon chip on copper (Power LEDs)
- 1000 cycles, air-air – non-encapsulated - 40/125° C, 30min dwell time
- Crack formation and delamination at the corners observed

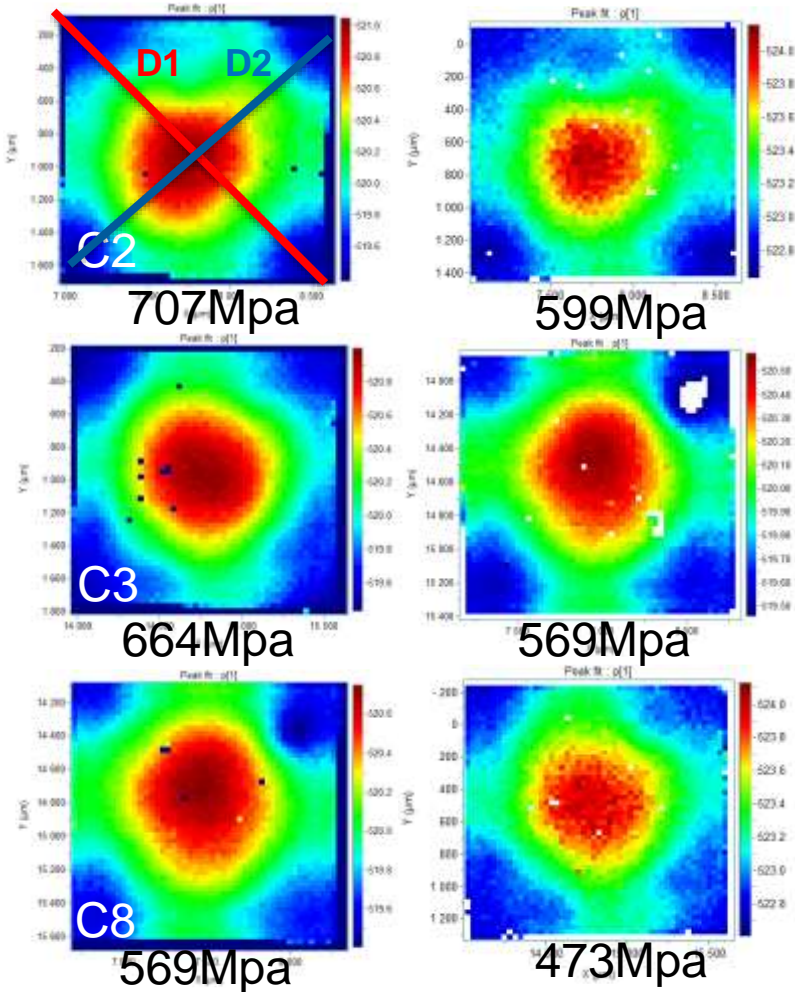


# Stress detected by $\mu$ -RAMAN spectroscopy

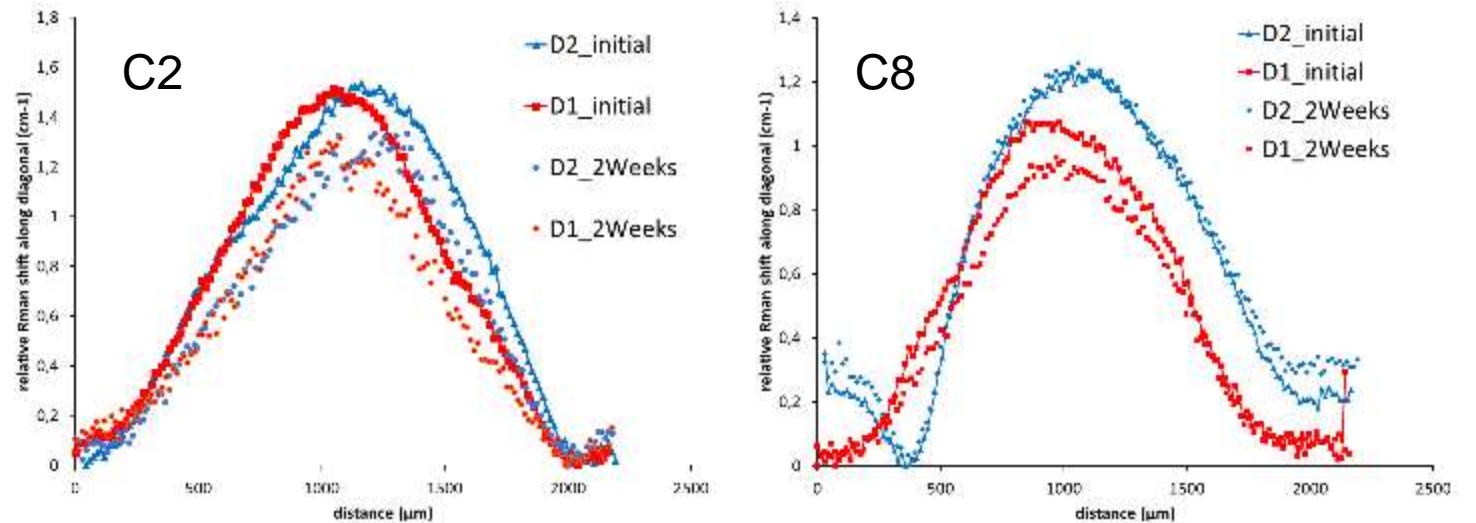
Copper Paste Development @ THI



after sintering      2 weeks after sintering



- Silicon test chips (1.5mm x 1.5mm) sintered on copper plates with THI copper paste
- $\mu$ -RAMAN spectroscopy with 532 nm excitation wavelength
- Strain (stress) is measured by the RAMAN shift
- Secondary creep of copper interconnect can be measured





# High Stress Thermal Shock MOSFET

Copper Paste Development @ THI



- Air-Air – non-encapsulated - +175/-65° C, 30min dwell time
- No delamination observed by Scanning Acoustic Microscopy (SAM)

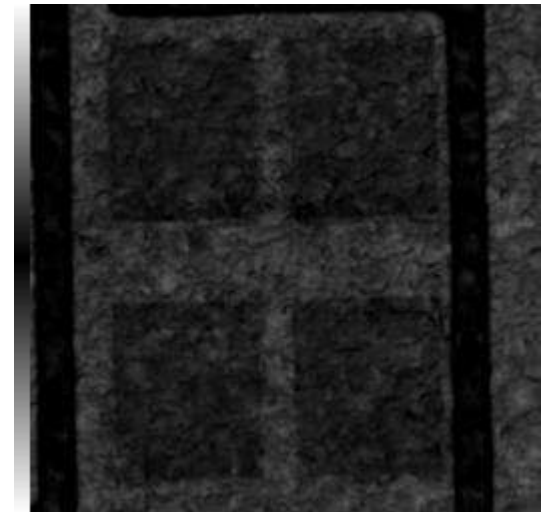
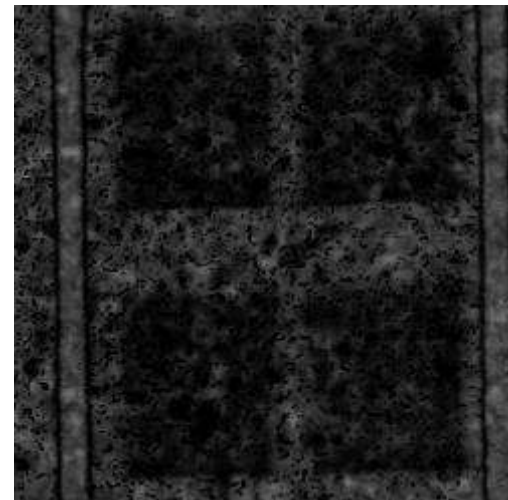
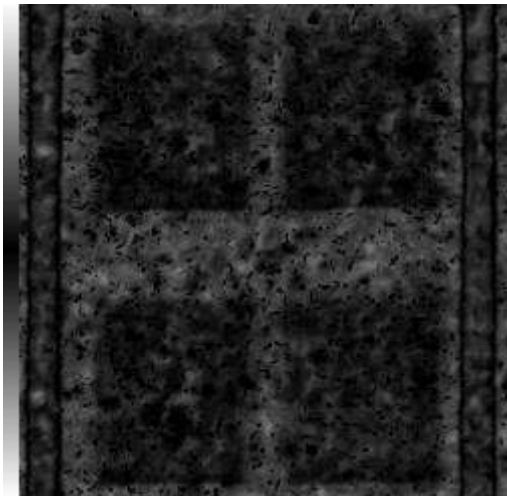
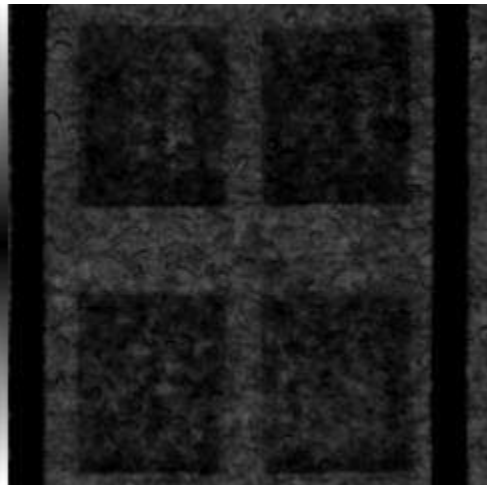


As sintered

500 cycles

1000 cycles

1500 cycles



# Large Area Bonding evaluation with NREL USA

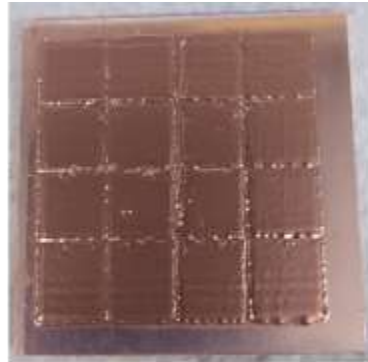
Copper Paste Development @ THI



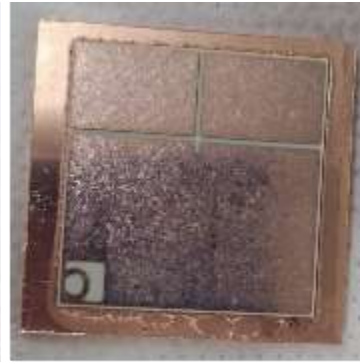
AMB with Cu metallization (1600mm<sup>2</sup> footprint)  
directly onto Cu baseplates



Stripes print pattern



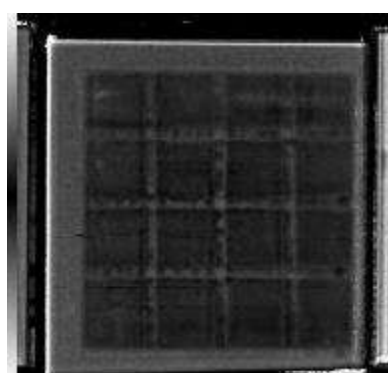
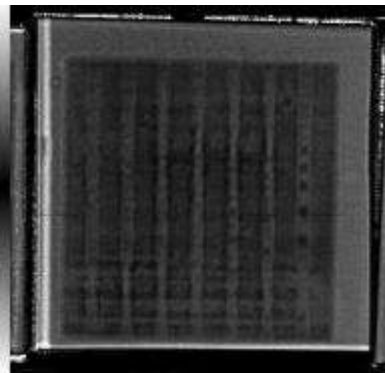
Squares print pattern



Final assembly



Budatec SP300  
sinter press

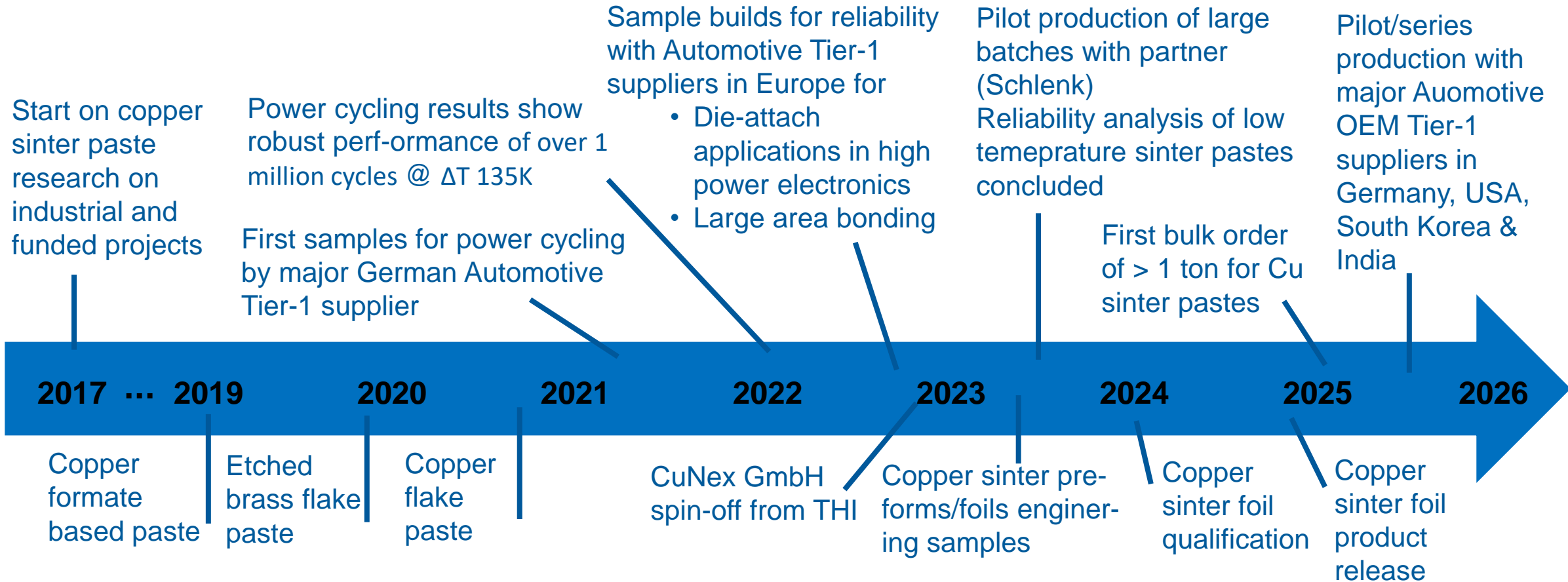


- SAM scans of the large area bonding show uniform sintering. No large voids/high porosity.
- Pre-drying – 15min in nitrogen @ 100° C
- Sintering – 5 min @ 275° C under nitrogen and 20 MPa bonding pressure

# Conclusion – History – Roadmap



Copper Paste Development @ THI



**PrLoMa** – partical enforst loders and copper sintring

**IQLED** – low tmpratur copper sintering

**ADDIRA** – Cu conductive inks & pastes for ADAS applications

**MaWisKI** – AI based prediction of material properties & performance

**DFG** – Cu sinter paste

**Copperfield** – hybrid Cu sinter paste

**CuNex:** Activated Copper Foil

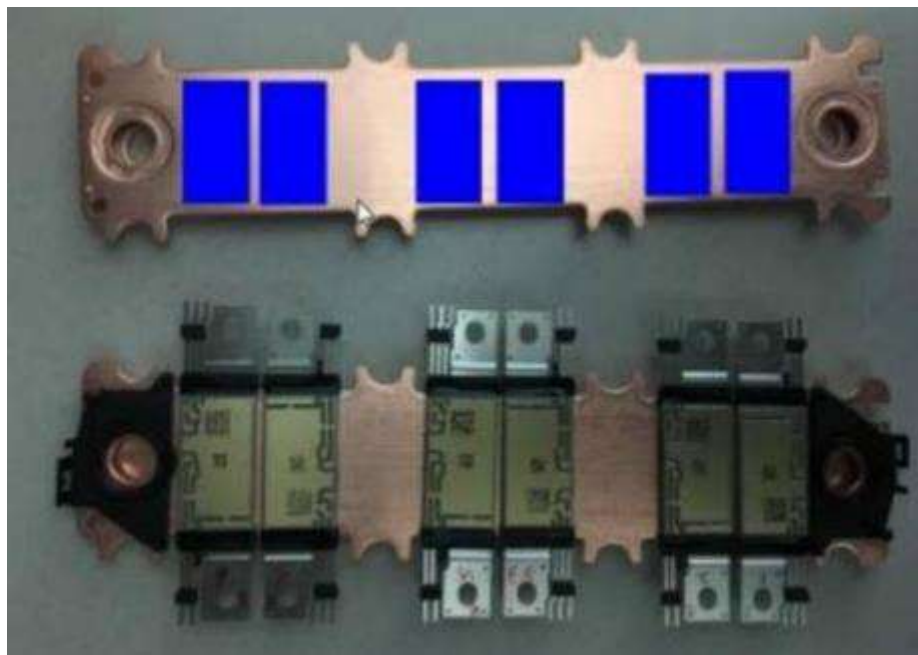
**JoinCuNext** – Coated flakes



# Thanks for your attention

Contact: [Gordon.elger@thi.de](mailto:Gordon.elger@thi.de)





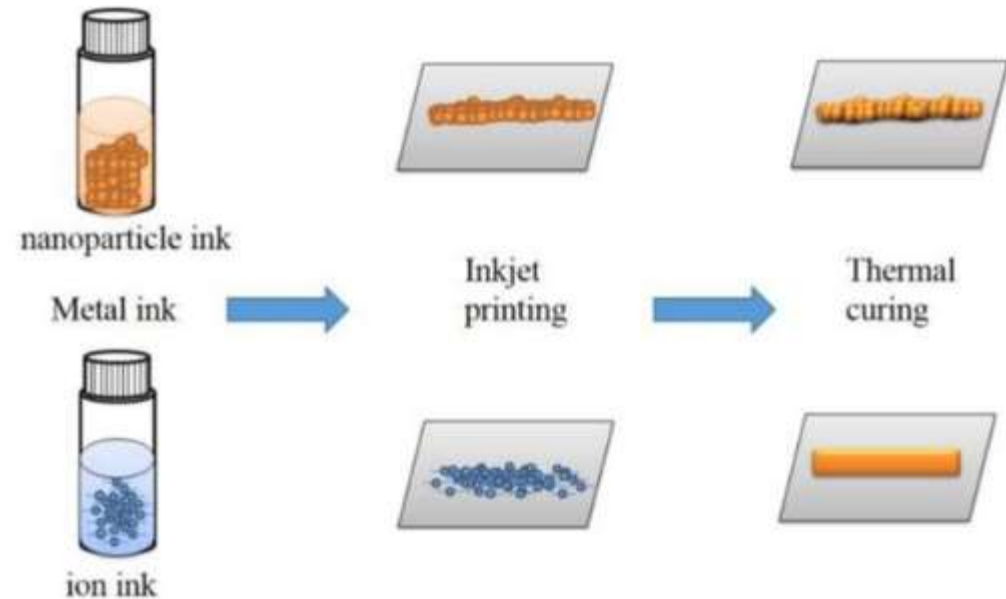
# Motivation

## Inks for Printed Electronics

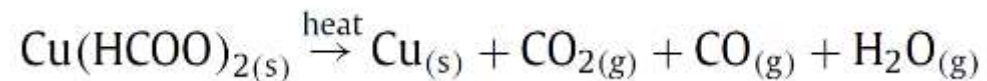
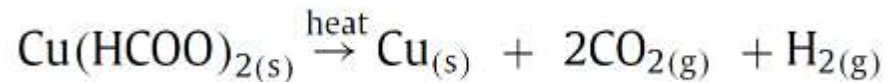


- **Driven by organic flexible substrates with low degradation temperature**
  - metallization process at low temperature
  - use of metal nanoparticle, metal organic complexes (usually Ag, Au but also Cu)

- **Copper Nanoparticle inks**



- **Metal-organic decomposition inks, e.g. copper formiate**



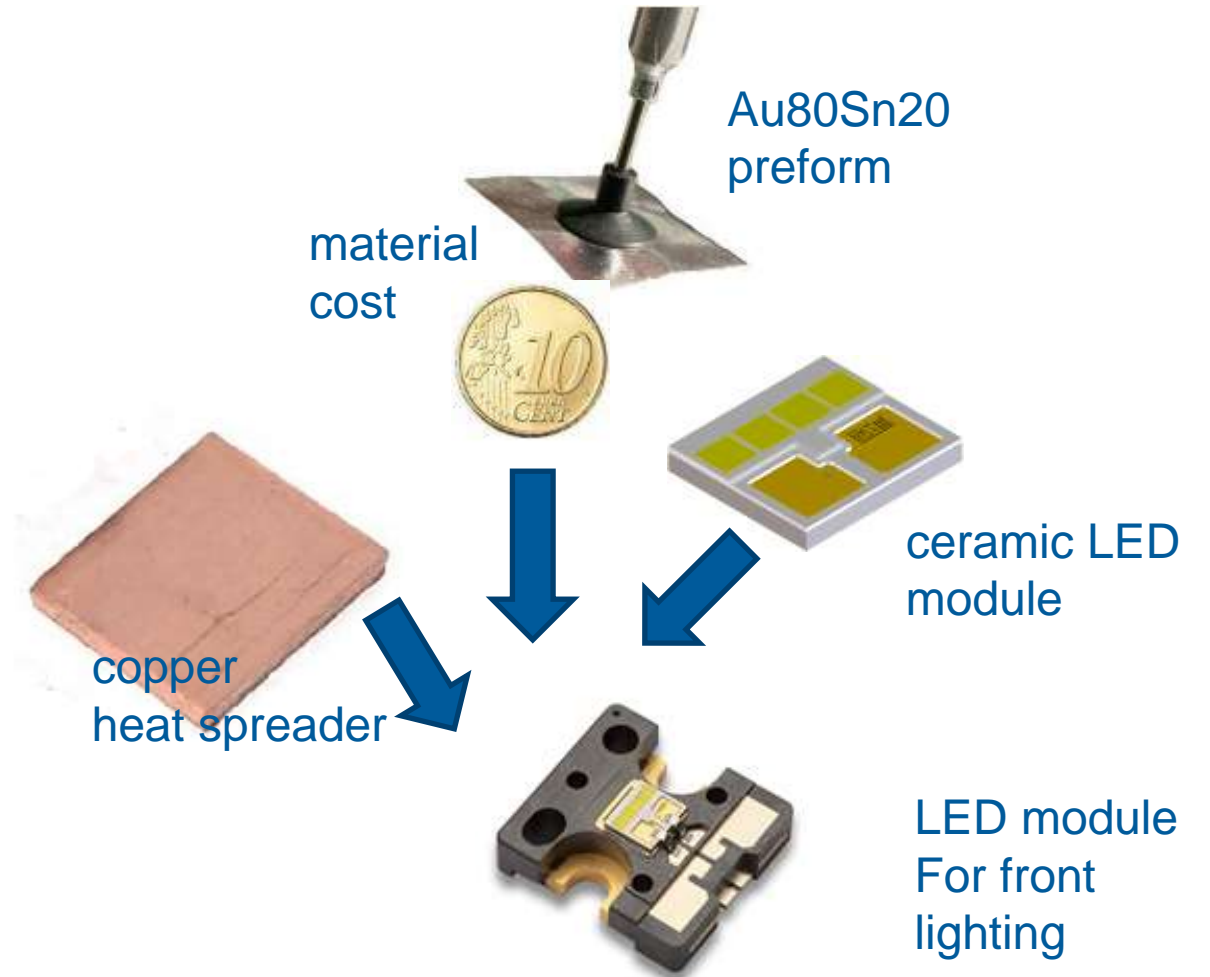
In dependence of binder/solvent temperature of decomposition  $150^\circ\text{C} \leftrightarrow 250^\circ\text{C}$

# Motivation

## *Replacement of expensive AuSn*



- For heat management ceramic carrier is mounted on copper heat spreader
- Due to thermomechanical mismatch of copper and ceramic large thermomechanical stress
- AuSn used as solder with high fatigue resistance (yield strength 200MPa)
- Replacing AuSn solder by copper paste
- Process requirement:
  - Temperature < 320°C
  - Time < 30s





# Motivation



## *Benefits of Copper Sintering*

- **Pure Copper Interconnect**
- **Lower electro migration compared to silver**
- **Potentially low cost material**
- **Different application with different requirements**
  - High stress application, e.g. AuSn replacement (shear strength 100MPa)
  - Low stress application, e.g. replacement of high lead containing solder (shear strength roughly 20MPa)
  - High temperature application
  - Interconnect formation at low temperature with high temperature working condition
    - Application: low stress assembly, integration of components on organic substrates

# Copper Sintering: Nanostructured Copper Flakes



## *General Concept of Surface Activation*

- From a thermodynamic point of view sinter bonding is driven by temperature and surface energy reduction.
- For copper, sintering at 275°C the homologous temperature is with roughly 0.4 relatively low
- Important driving force comes from the high surface energy and curved surface inherent to a powder.
  - Small particles have more surface energy and sinter faster than large particles.
- The initial stage of sintering corresponds to neck growth between contacting particles
  - Curvature gradients normally dictate the sintering behavior.
- The intermediate stage corresponds to pore rounding and the onset of grain growth.
  - During the intermediate stage the pores remain interconnected
- Final stage sintering occurs when the pores collapse into closed spheres, giving a reduced impediment to grain growth.
  - Usually the final stage of sintering starts when the component is more than 92% dense.
- During all three stages, atoms move by several transport mechanisms to create the microstructure changes, including surface diffusion and grain boundary diffusion.
- Sintering models include parameters such as particle size and surface area, temperature, time, initial density, pressure and atmosphere.

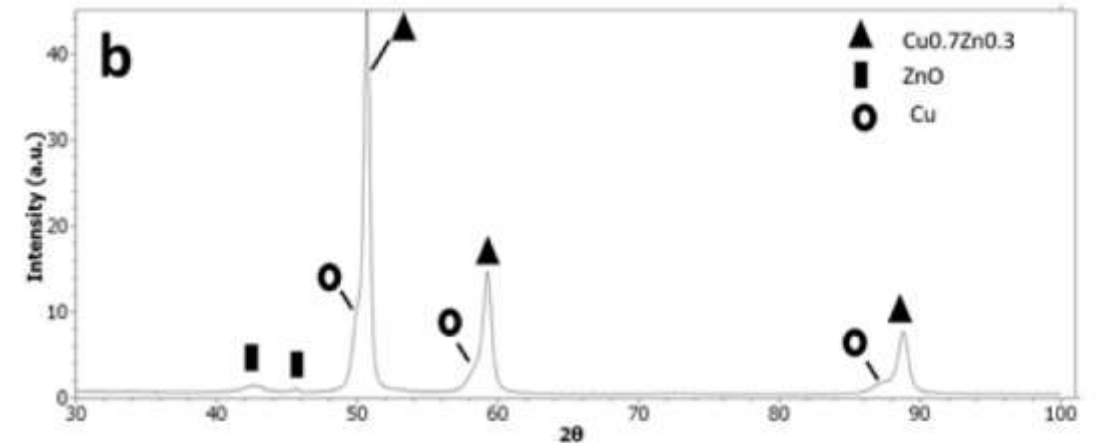
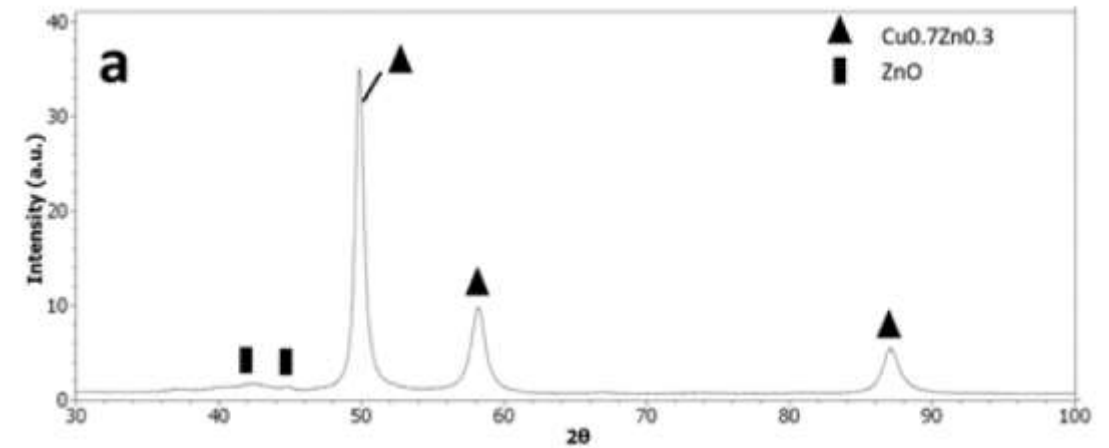
# Copper Sintering: Nanostructured Copper Flakes



*XRD before and after etching*

- For  $\alpha$ -brass Zn is dissolved in the Cu crystal, i.e. a solid solution with zinc atoms located at normal lattice sites
- The original brass powder shows the typical peak of  $\text{Cu}_{0.7}\text{Zn}_{0.3}$
- No Oxides are found in the original powder because it is protected by 1.5wt% of steric acid
- After etching partly pure Cu is observed

a) XRD before etching Cu30%Zn



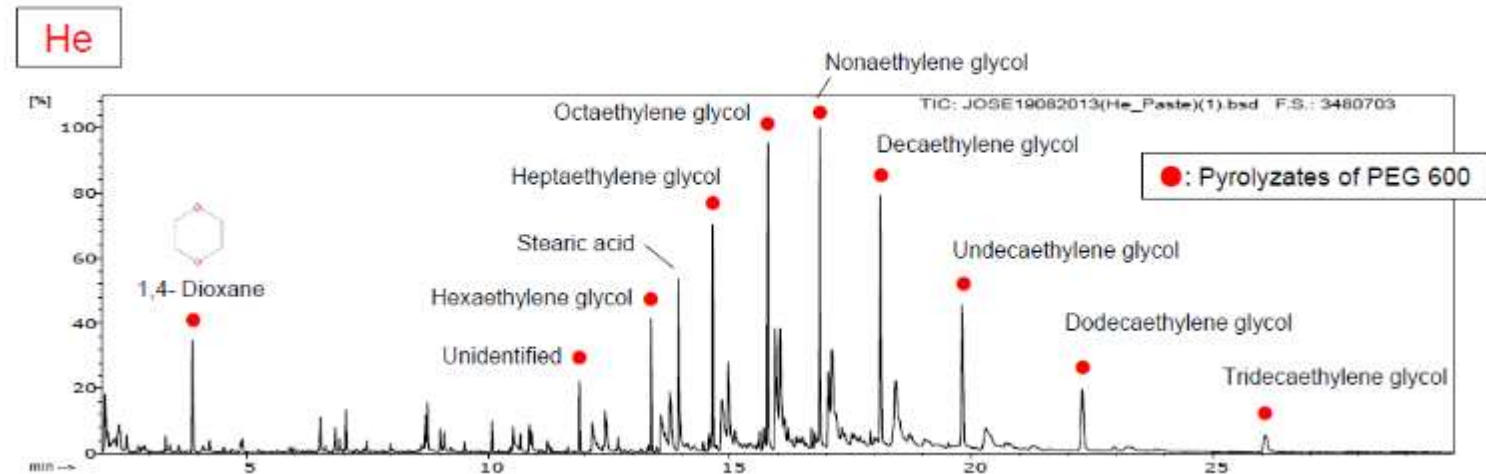
b) XRD after etching Cu30%Zn

# Copper Sintering: Nanostructured Copper Flakes

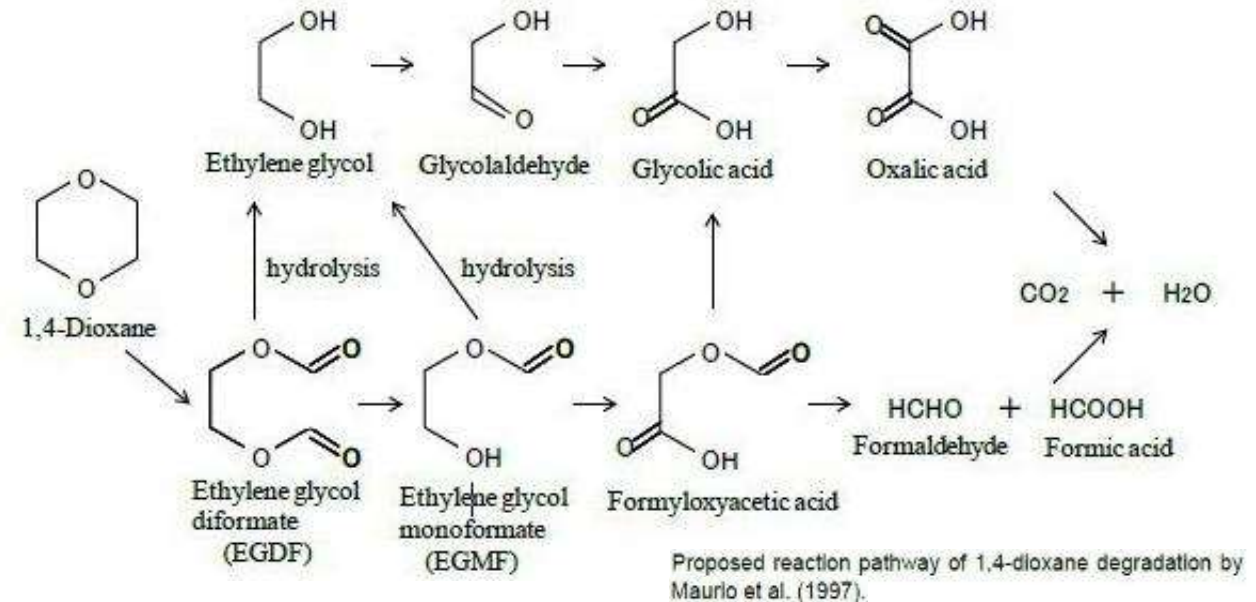


Reducing effects of the binder – possible phenomenon

- Boiling temperature >250C
- Decomposition of PEG600 takes place above boiling point and depends from presence of oxygen
- Prevent agglomeration
- Reducing effect



Sheared copper interface using (d) PEG600 (e) terpineol as binder

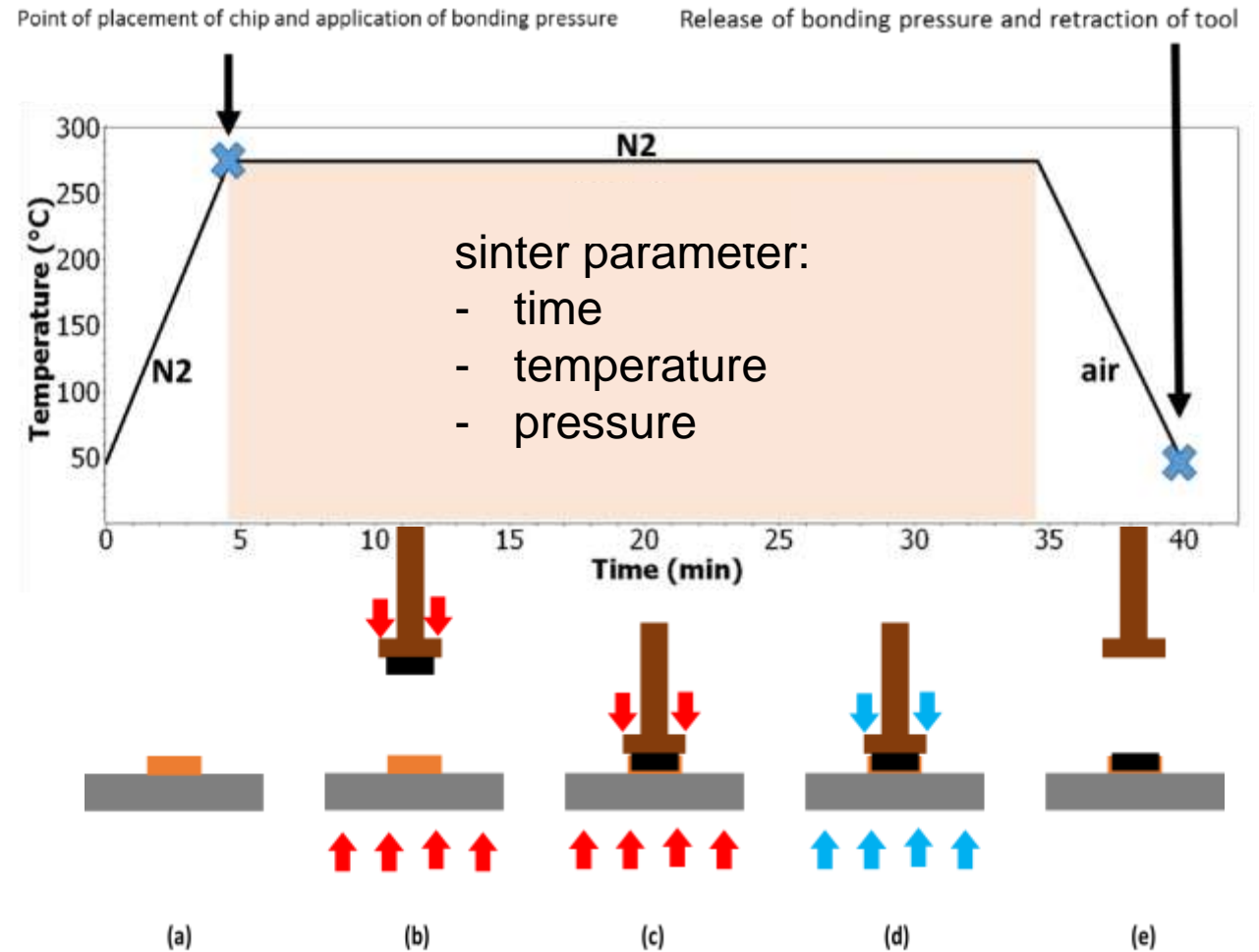


# Copper Sintering: Nanostructured Copper Flakes



## Sintering process & assembly

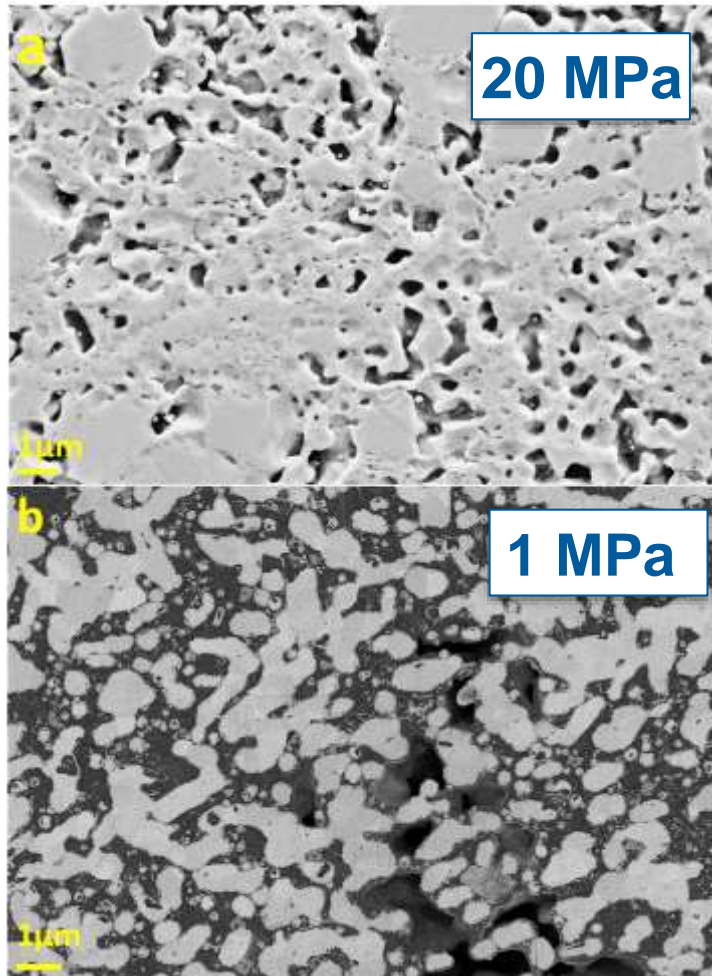
- 3,5 mm<sup>2</sup> Cu test chips and 100mm<sup>2</sup> substrates of 1mm thickness
- a) Stencil printing
- b) Ramp up to sintering temperature at 1K/s
- c) Place the chip once sintering temperature is reached.
- d) Bond with 20MPa pressure for 30min
- e) Release chip
- In production a press is used and process is performed on panel level



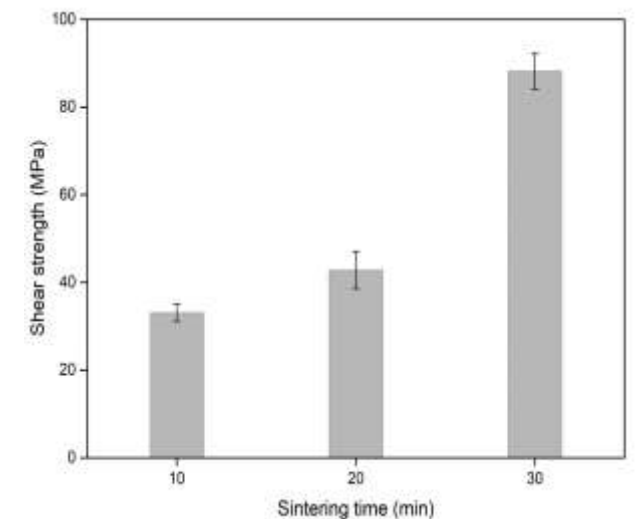
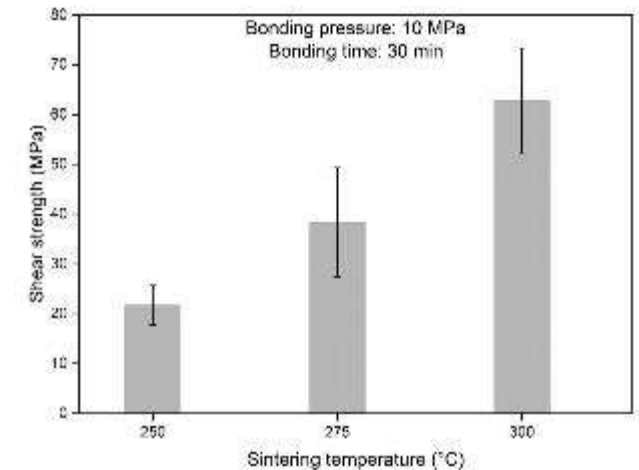
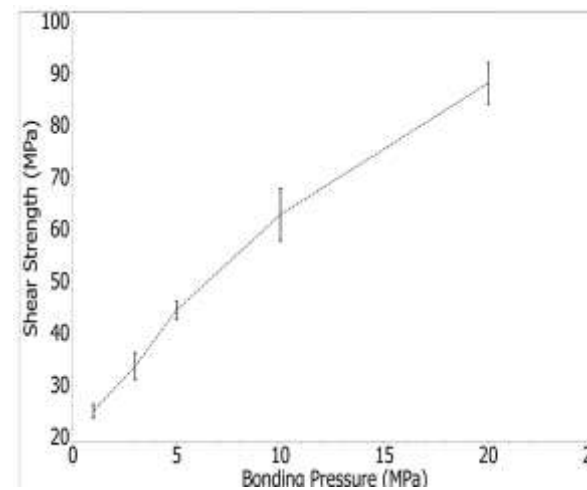
# Copper Sintering: Nanostructured Copper Flakes



## Results



- Shear strength over 80MPa
- Expected parameter dependence
- Porosity depend on bond force

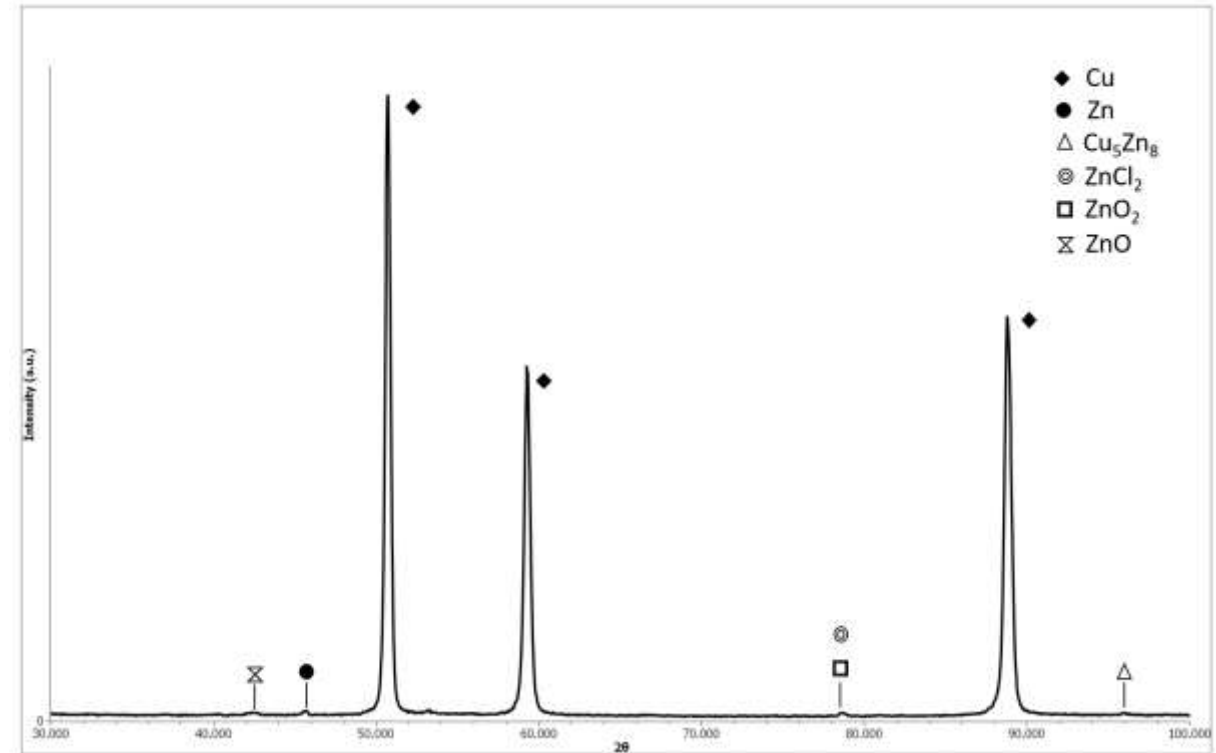


# Copper Sintering: Nanostructured Copper Flakes



## *XRD on Sheared Interface*

- Risk of remaining Zn
- Risk of residual Cl
- Presence of Cu and Zn oxides



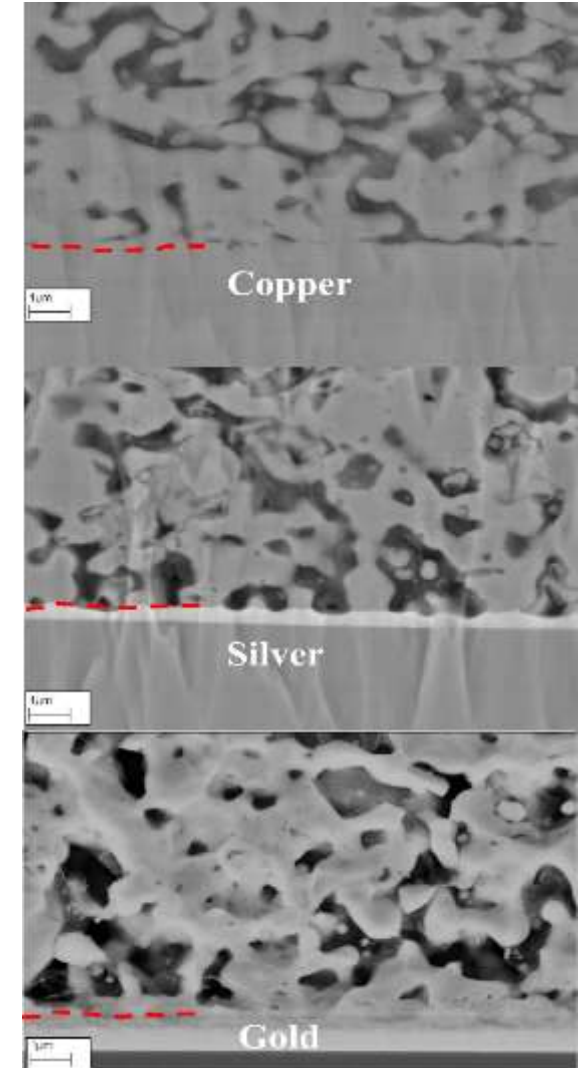
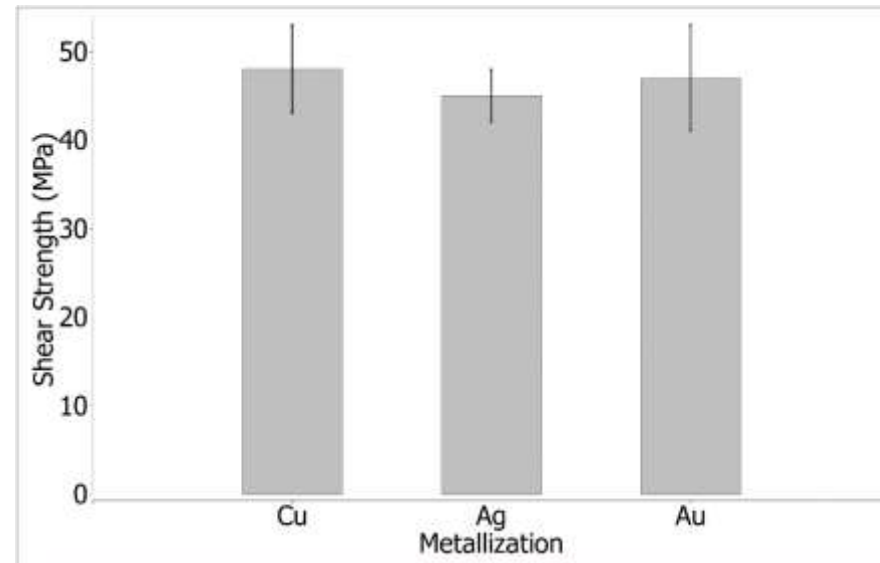
# Copper Sintering: Nanostructured Copper Flakes



## *Compatibility with typical metallization*

- Impact of surface metallization on the shear strength of the sintered interconnect under bonding conditions of 5 MPa bonding pressure, 275°C sinter temperature, 30 min sinter time and nitrogen atmosphere .

- Copper
- Electroless NiAg
- Electroless NiAu





# Copper Sintering: Nanostructured Copper Flakes



## Densification

### ■ Results are in line with recent models

- Densification is a function of (Mackenzie-Shuttleworth model)

$$\frac{d\rho}{dt} = \frac{3}{2} \left( \frac{\gamma}{r} + P_{\text{applied}} \right) (1 - \rho) \left( 1 - \alpha \left( \frac{1}{\rho} - 1 \right)^{\frac{1}{3}} \ln \left( \frac{1}{1 - \rho} \right) \right) 1/\eta$$

(sintering pressure  $P_{\text{applied}}$ , surface energy  $\gamma$ , particle radius  $r$ , geometrical constant  $\alpha$ , density  $\rho$ , and densification viscosity  $\eta$ )

- Pore mobility

$$M_p^s = \frac{D_s \delta_s \Omega}{\pi r^4 k T}$$

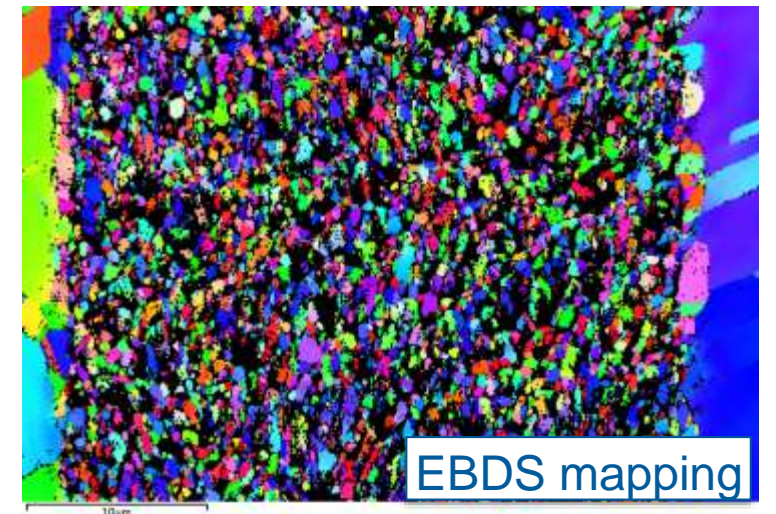
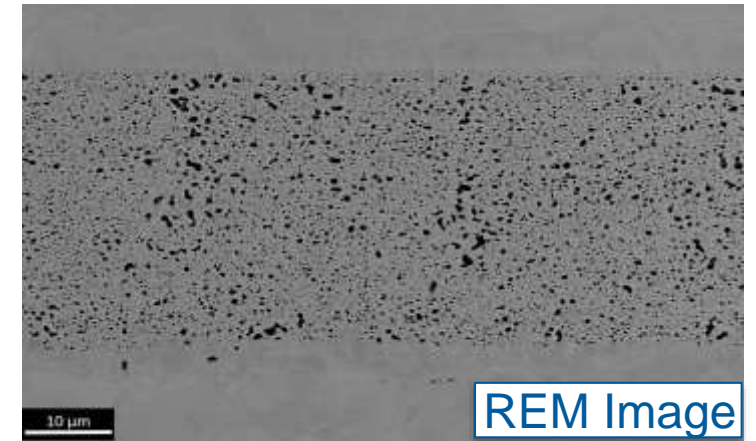
( $\Omega$ : atom volume,  $\delta_s$ : surface thickness,  $r$ : pore radius,  $T$ : temperature,  $k$ : Boltzman constant,  $D_s$ : surface diffusion coefficient)

### ■ Decrease of pores in the final sintering stage

- With an assumption of circularity of the pores, the radius of the pore is calculated to be an average value of 0.05  $\mu\text{m}$ .

The average grain size calculated by EBSD is 0.6  $\mu\text{m}$ .

5 MPa bonding pressure at 275 °C for 30 min



# Copper Sintering: Nanostructured Copper Flakes

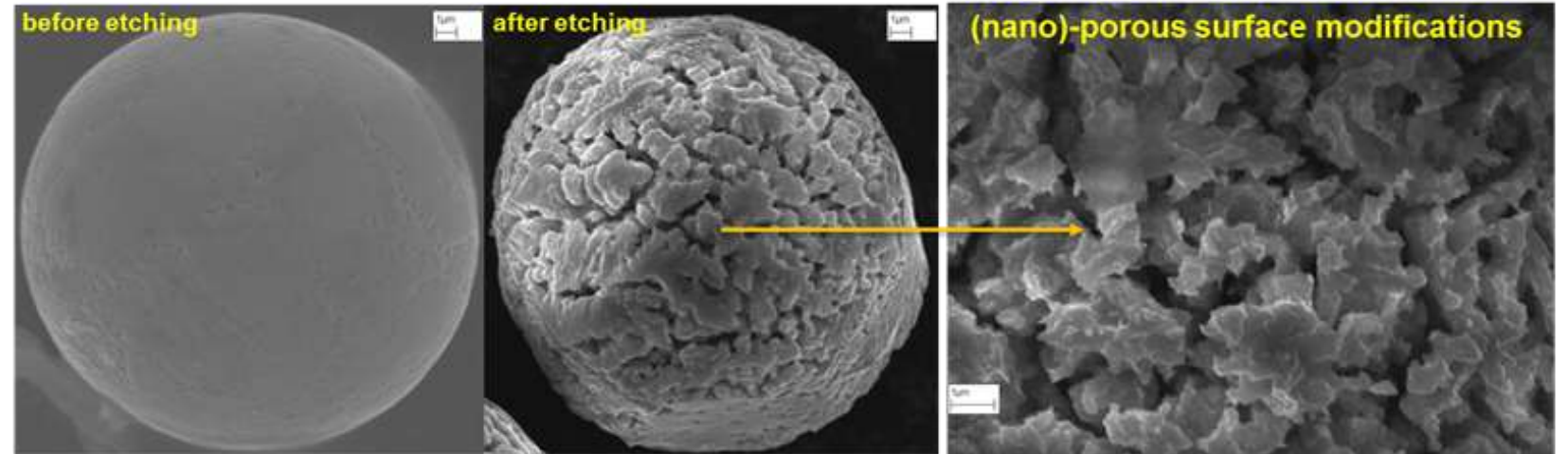


*Brass and Bronze by Hydrochloric Acid*

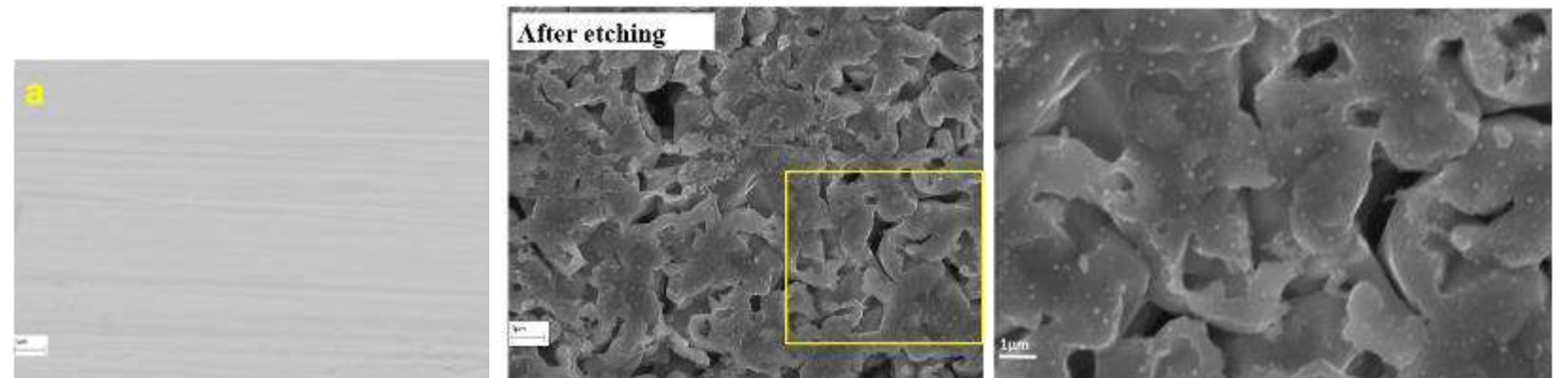
- Nobel Cu remains and is separated from Sn or Zn



- Structured surface of 25 $\mu\text{m}$  bronze particle after etching



- Structured surface of bronze substrate



# Copper Sintering: Nanostructured Copper Flakes



*Compatibility with typical metallization*

- **Control of porosity by pressure and time**
- **Higher Porosity**
  - reduces shear strength
  - increases elasticity, i.e. reduces E modulus)
- **Design of optimized interconnect for thermomechanical fatigue**

# Copper Sintering: Copper Formiate Decomposition



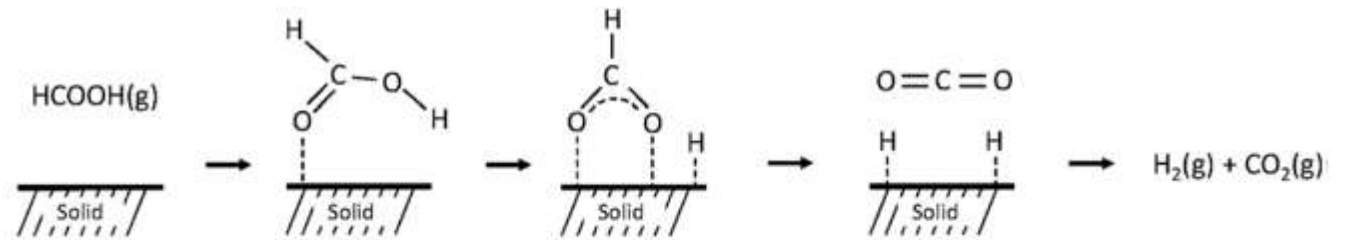
## Formiat Decomposition

### Formic acid decomposition

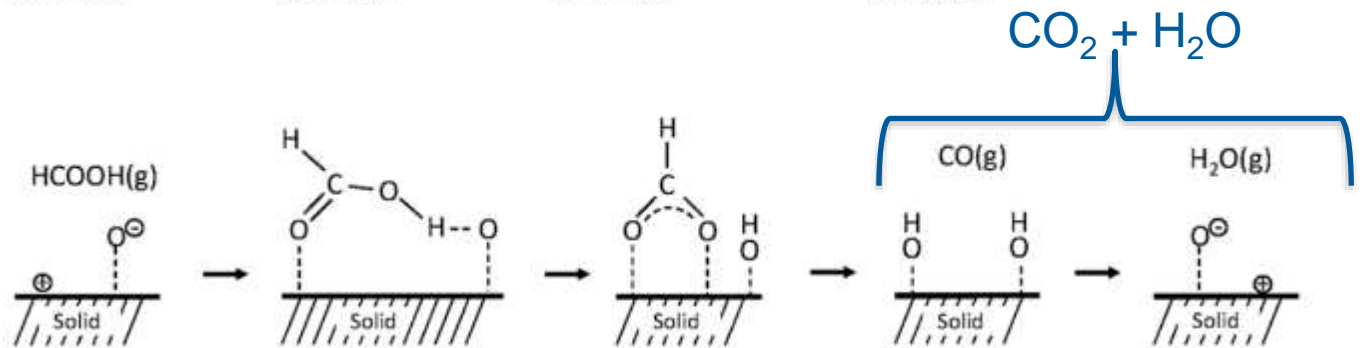
- Dehydrogenization  $HCOOH \rightarrow H_2 + CO_2$   $\Delta G^0 = -32.9 \text{ kJ/mol}$  (Gl.1)
- Dehydration  $HCOOH \rightarrow H_2O + CO$   $\Delta G^0 = -20.7 \text{ kJ/mol}$  (Gl.2)

### Catalytic interaction with metal surfaces

Pure metal



Metal oxide

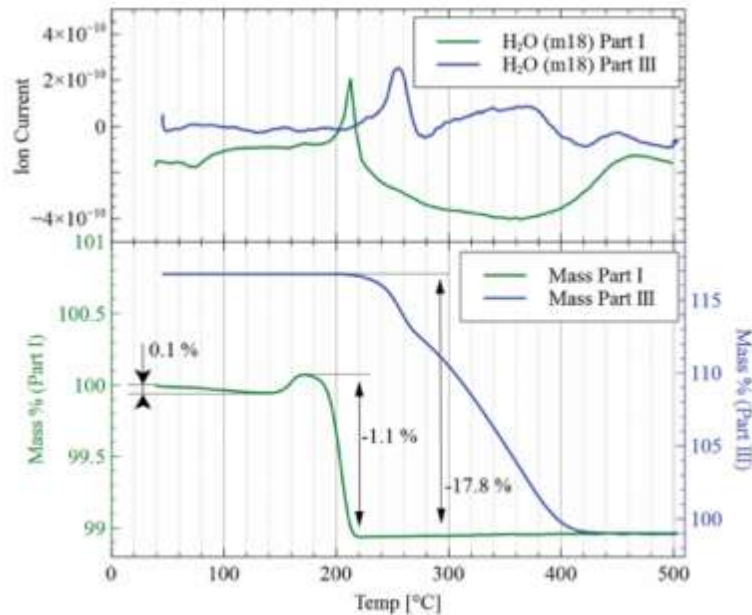


# Copper Sintering: Copper Formiate Decomposition

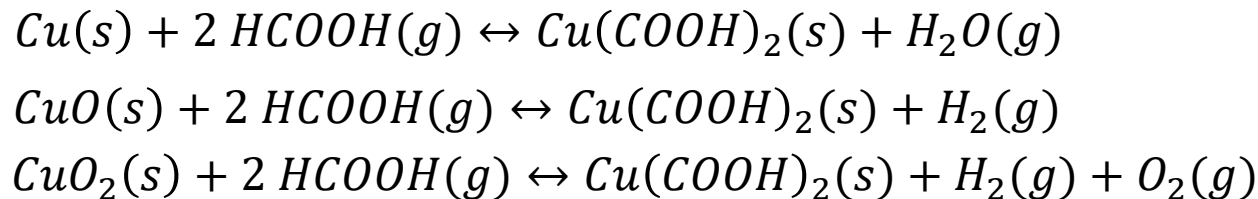
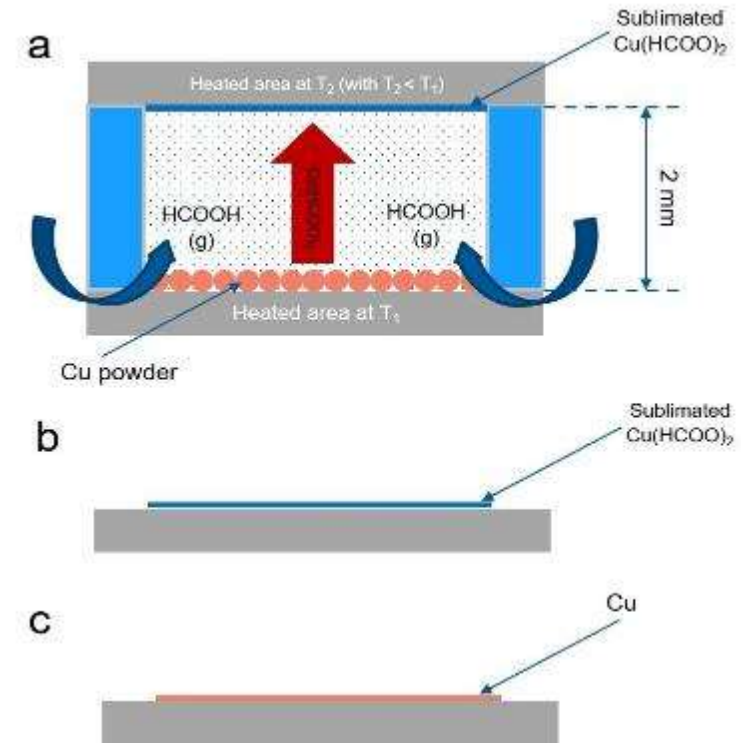
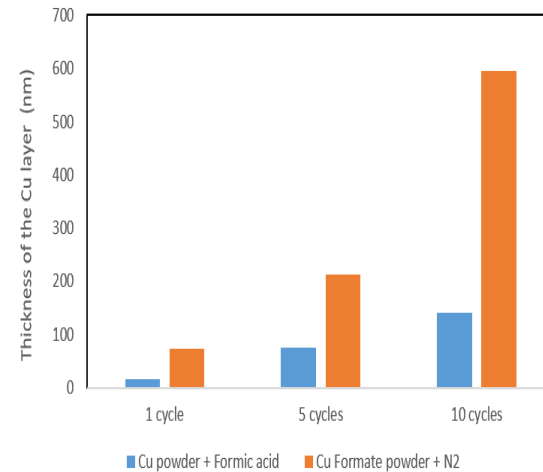


Formiat Desorption and Sublimation – Camical Vapour Deposition

## TGA of Copper under formic acid vapor



## Deposition/Sublimation of copper formate and decomposition to copper



# Copper Sintering: Copper Formiate Decomposition

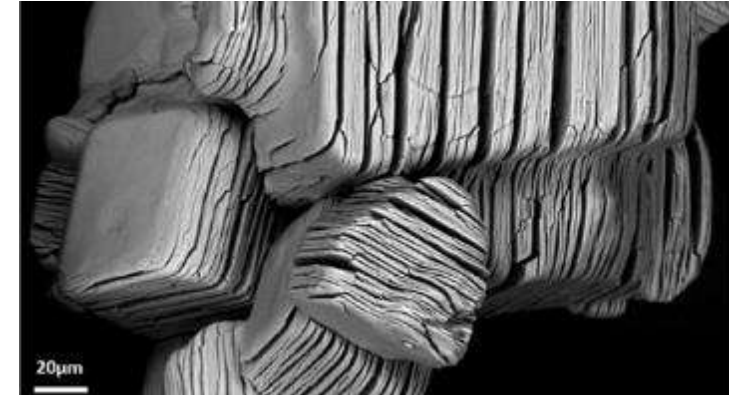


*Formiat Desorption and Sublimation – Camical Vapour Deposition*

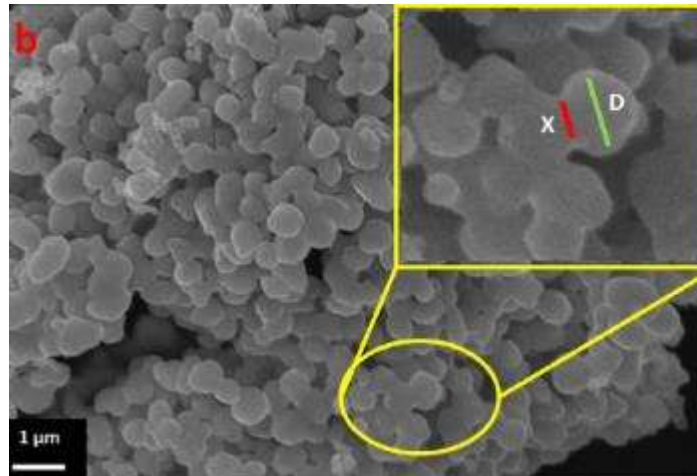
- Commercial copper-2-formiate, grinded to 1 $\mu$ m particle
- Scaling model
  - Sinter time t scales with particle size D

$$t_2/t_1 = (D_2/D_1)^n$$

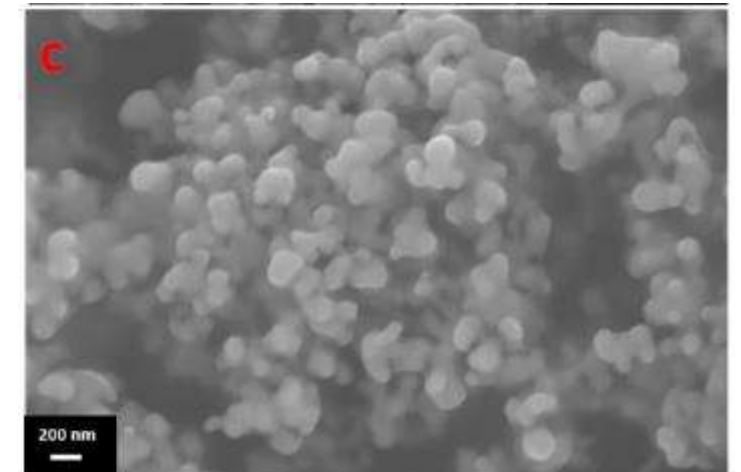
- Binder depended copper particle diameter
  - No binder 500nm
  - PEG500 200nm



Copper Formiate before grinding



Decomposition, no binder



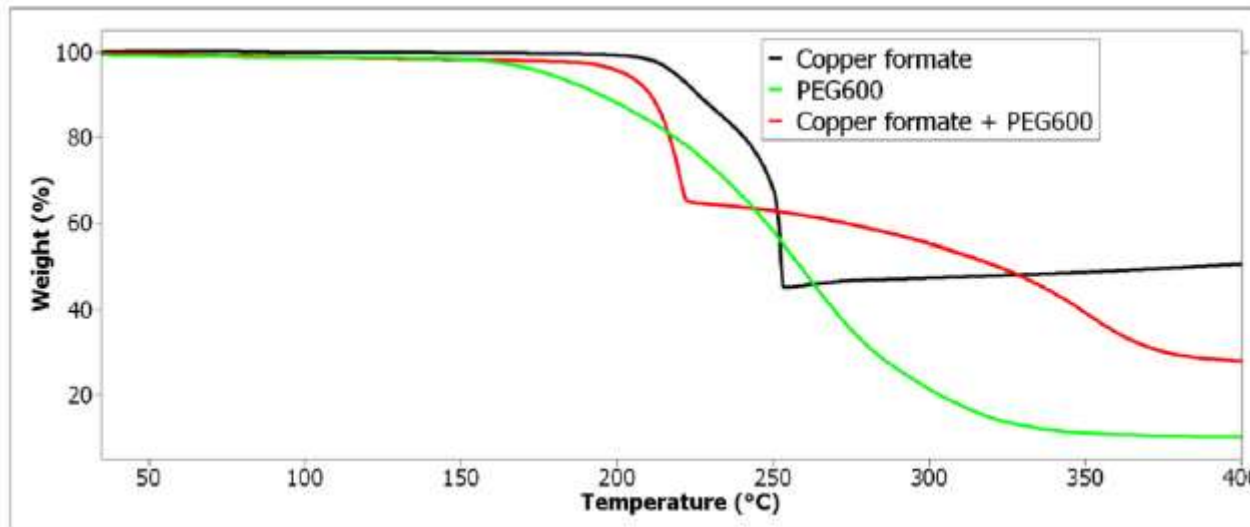
Decomposition in PEG600

# Copper Sintering: Copper Formiate Decomposition

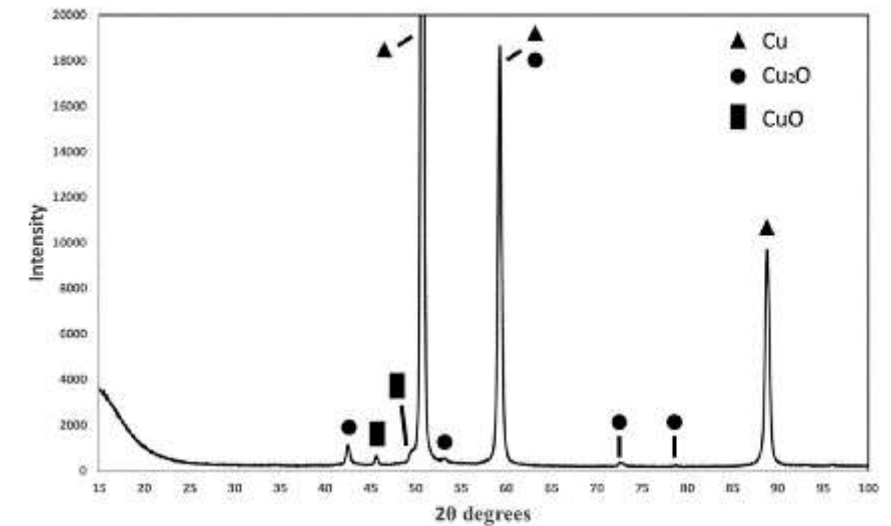


## *Binder Dependent Decomposition Temperature*

- Decomposition temperature is reduced by 20°C by PEG600 due to earlier volatilization of free carboxyl groups dissociated already at lower temperatures by the presence of PEG600.
- During decomposition under air small amount of oxide is formed, i.e. oxidation protection required



TGA of copper(II) formate (no binder, PEG600, copper(II) formate in PEG)



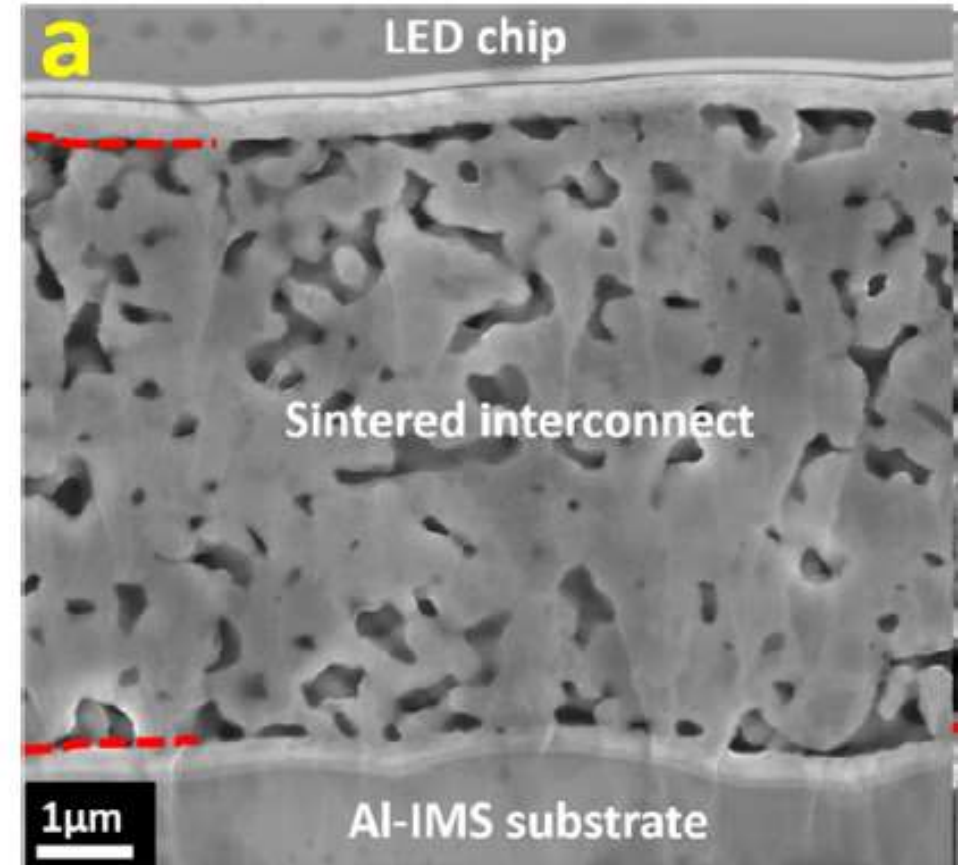
XRD analysis of the nanoparticles produced via thermal decomposition of the copper(II) formate. The pattern is recorded with the crystals under air, i.e. under 21% oxygen by volume.

# Copper Sintering: Copper Formiate Decomposition



## *Interface and Shear values*

- **Test sample: LED on Al-IMS**
- **Same process as with etched copper particles**
  - 275°C, 20MPa, 30min
- **Well sintered interconnect**
- **Function of binder: development of fine nano powder forming at low temperature**
- **Ongoing development of binder: inorganic binder as amino-2-propanol and amines like hexamine**
  - Reducing agent supporting the dissociation of carboxyl groups
  - Encapsulation of copper to reduce the growth





# Conclusion



# Formic Acid Decomposition

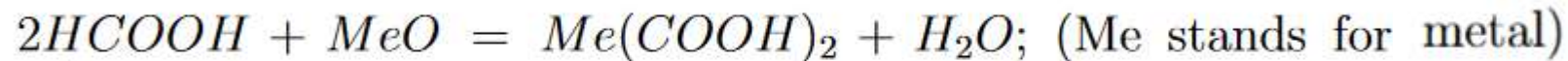


## Common insufficient explanation

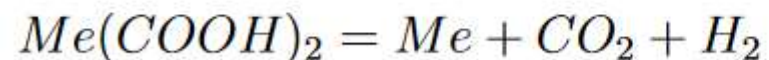
- Very common, the interaction of formic acid with metals is reported incorrectly, e.g.:

The reaction of formic acid with metal oxide is:

When temperature is more than 150°C,



When temperature is more than 200°C,



When the temperature is between 150 C and 200 C, formic acid reacts with solder oxide to form a carboxyl compound. When the temperature is higher than 200 C, the compound further decomposes into carbon dioxide and hydrogen and is excluded from the chamber by nitrogen purging.

# Formic Acid Decomposition

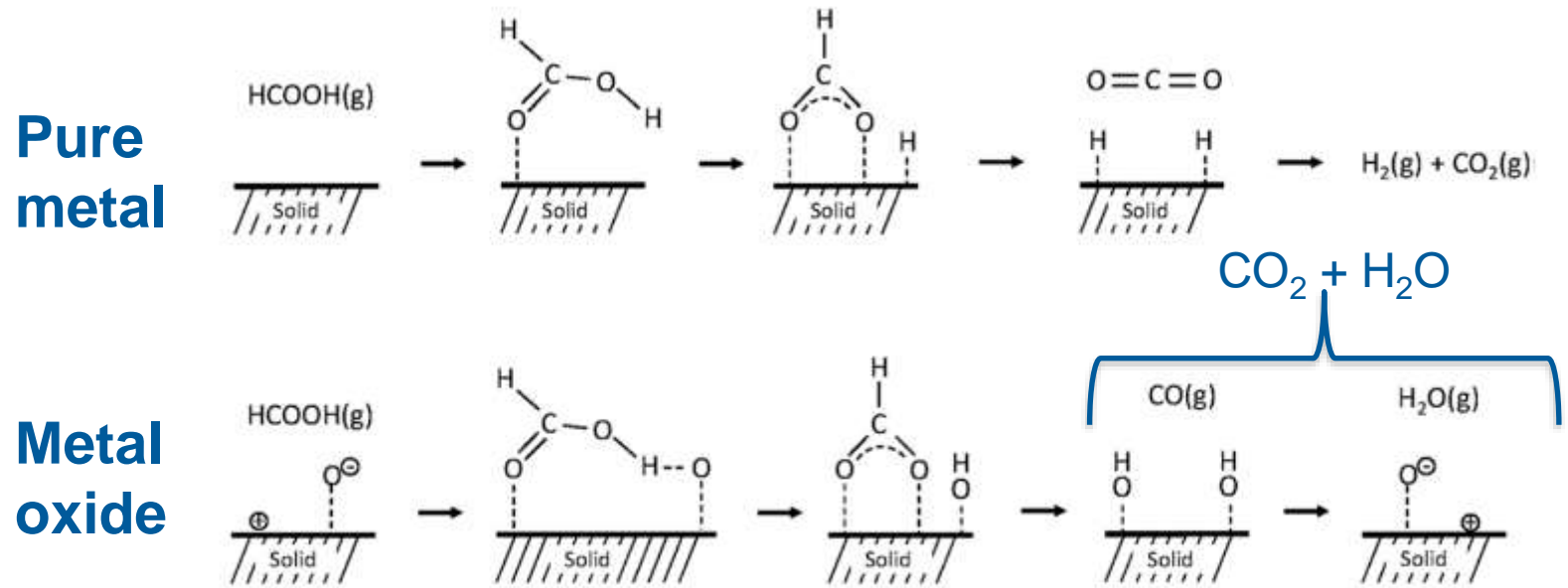


## Formic acid self decomposition

### Formic acid decomposition

- Dehydrogenization  $HCOOH \rightarrow H_2 + CO_2$   $\Delta G^0 = -32.9 \text{ kJ/mol}$  (Gl.1)
- Dehydration  $HCOOH \rightarrow H_2O + CO$   $\Delta G^0 = -20.7 \text{ kJ/mol}$  (Gl.2)

### Catalytic interaction with metal surfaces





- <https://advanceseng.com/concept-progress-intelligent-spindles/>

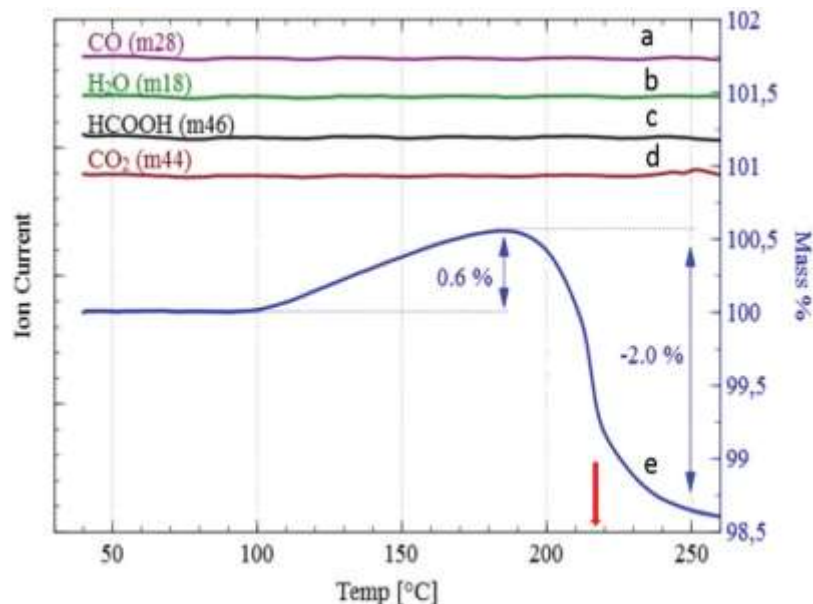
# Thermal Gravimetric Analysis



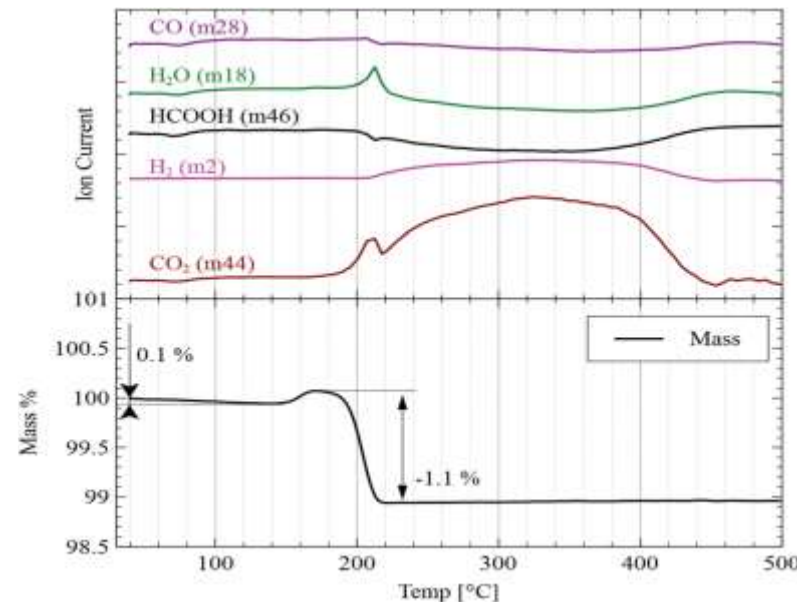
*Oxidized Metal powder under formic acid*

- Thermal gravimetric analysis under formic acid with mass spectrometer for analysis of gaseous decomposition products
- SAC powder (type 5) and weakly oxidized copper powder (type 6)

SAC (atomic mass Sn 118u)



Weakly oxidized Cu (atomic mass 63u)



- Mass reduction is too large to be explained by loss of oxygen
- CO<sub>2</sub> and H<sub>2</sub>O peaks found for copper but not for SAC

# Metal Formiate Evaporation



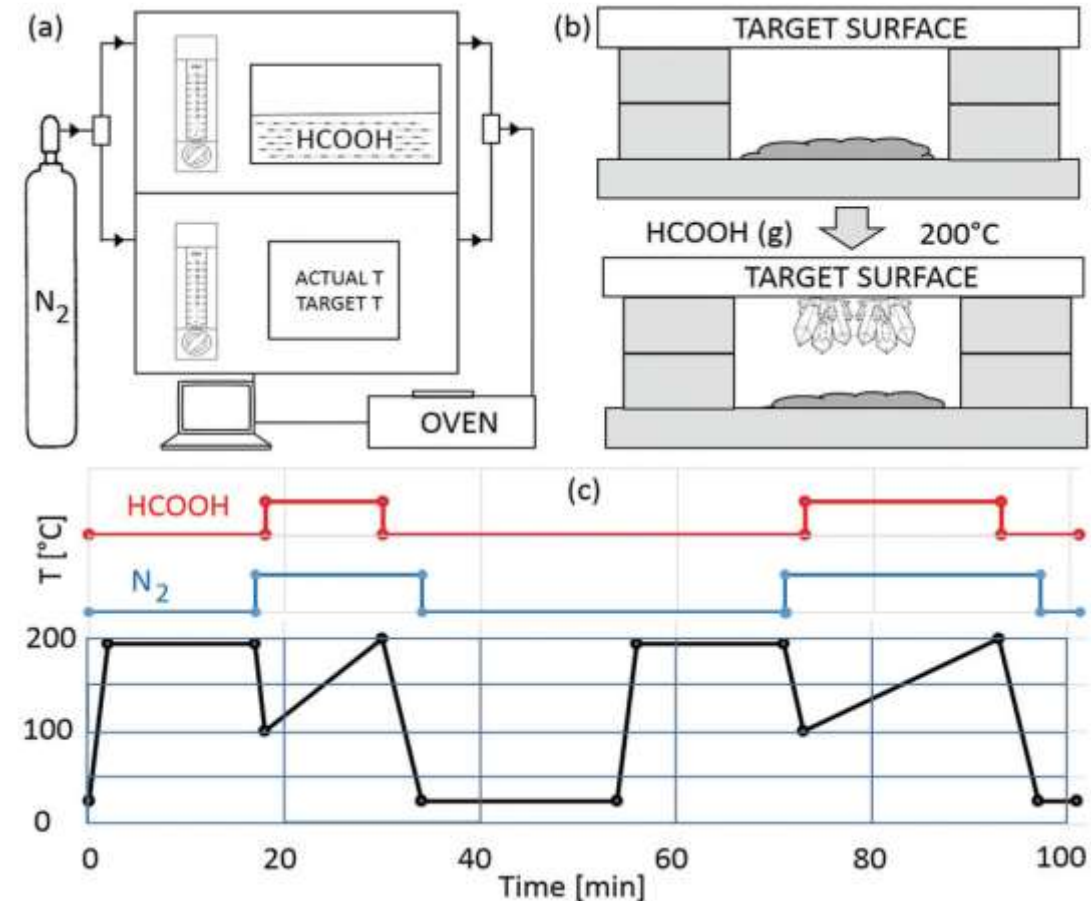
*Experimental setup to prove evaporation of metal formiate*

## ■ Experimental Setup

- Bottom glass plate
- Two spacer 2mm
- Top glass plate
- Metal powder on bottom glass plate
- Temperature top plate approx. 20°C below bottom plate

## ■ Temperatur profile similar to TGA measurement

- Variation of T-max and hold times

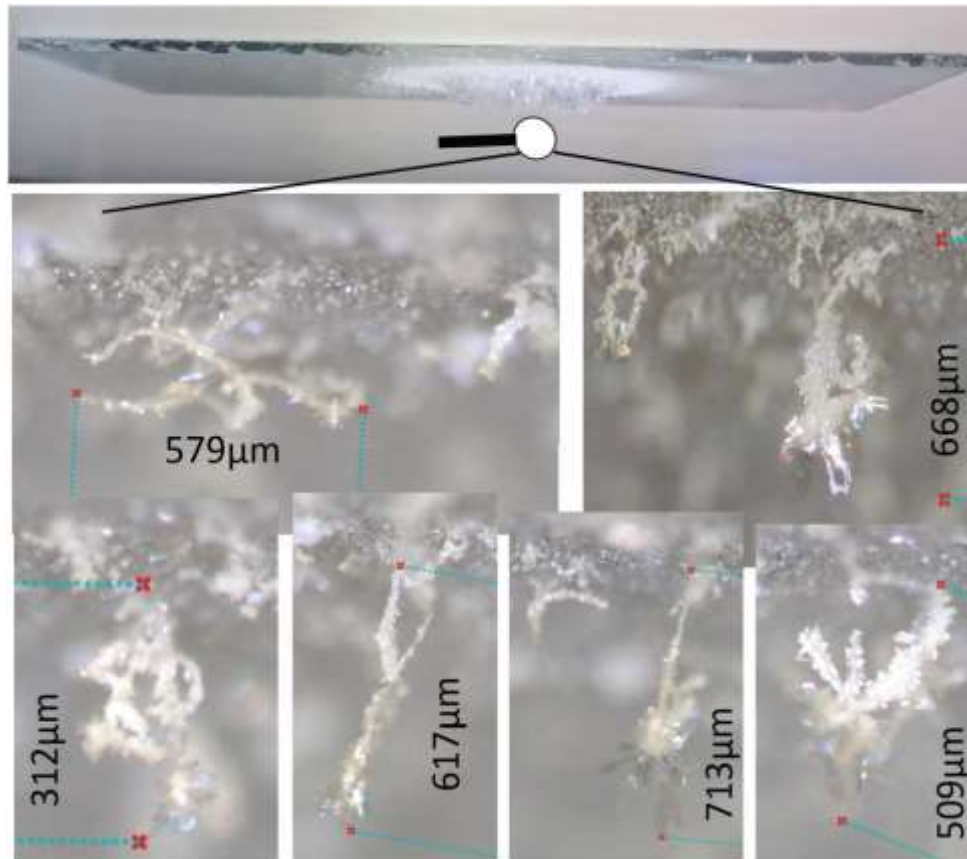


# Metal Formiate Evaporation

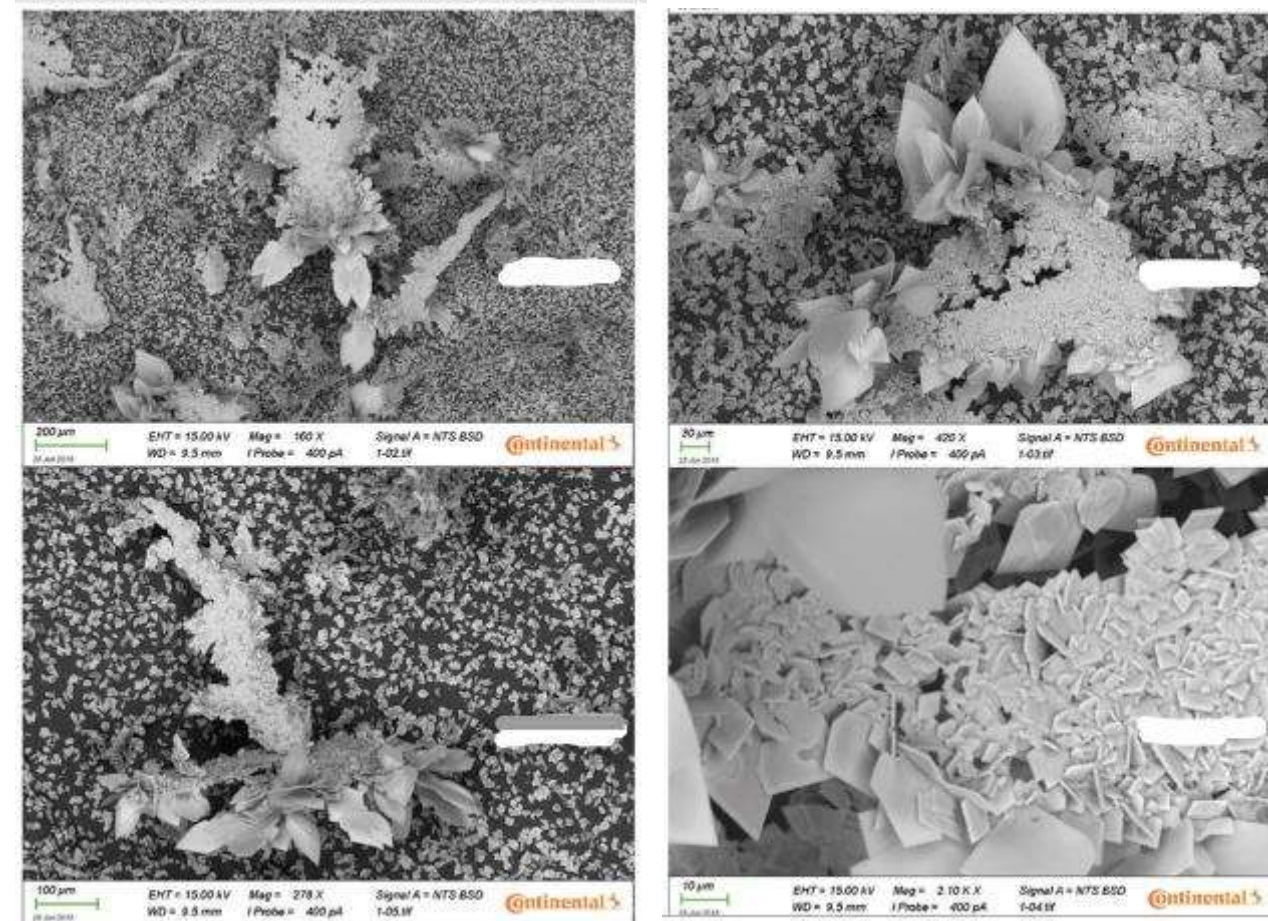
*Christall formation on top plate using SAC*



- Chrystal's grow on the top surface (SAC)



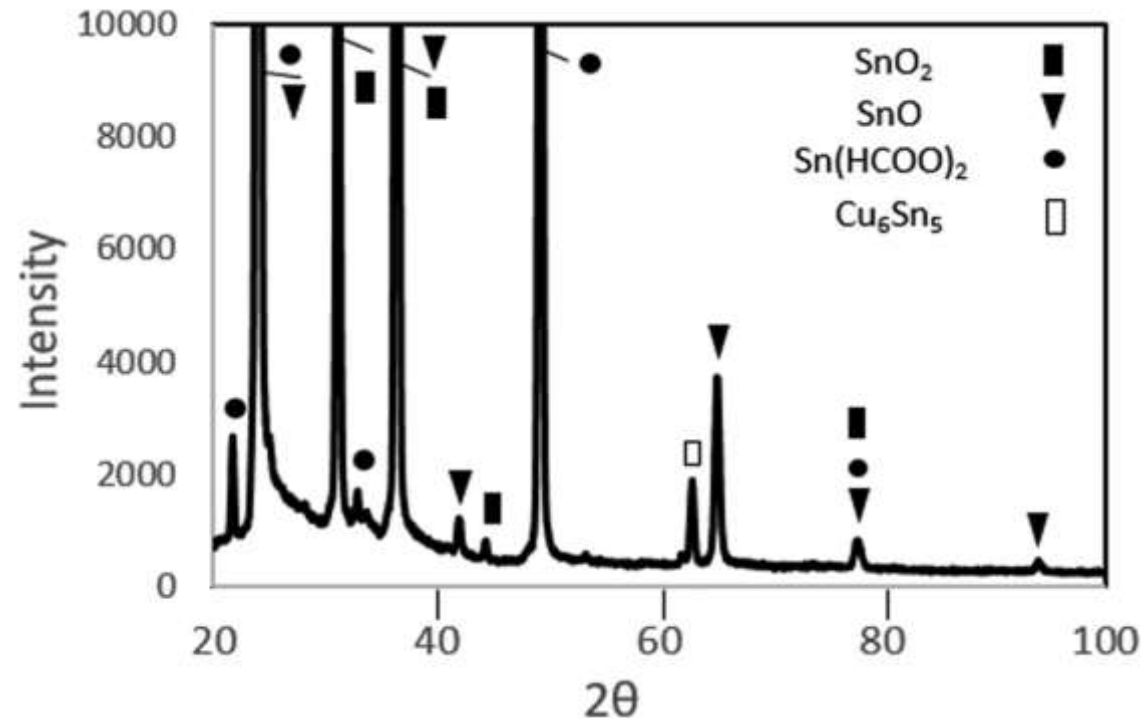
3D optical microscope



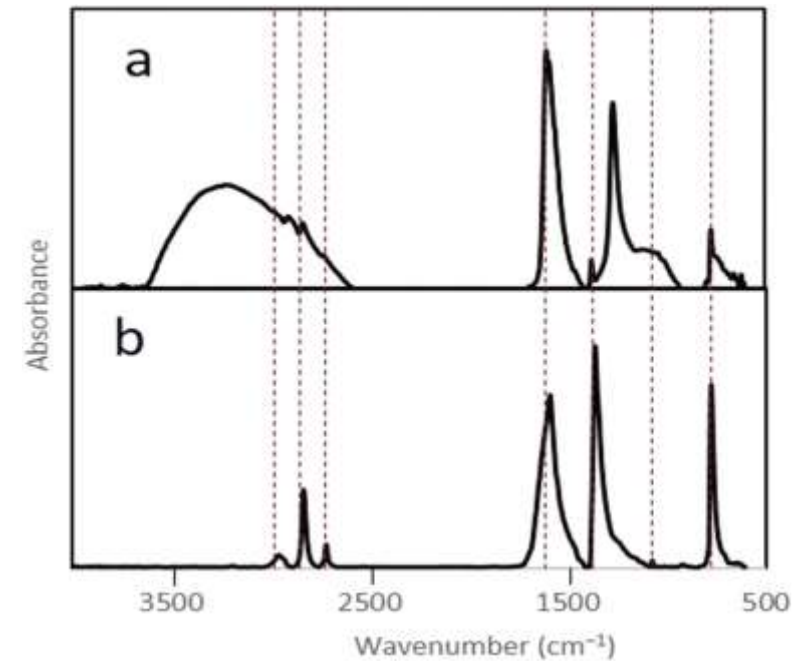
SEM microscope

# Metal Formiate Evaporation

*Analysis of crystals*



XRD analysis



FT-ATR Infrared spectroscopy  
a) Measured b) reference  $\text{NaHCOO}$

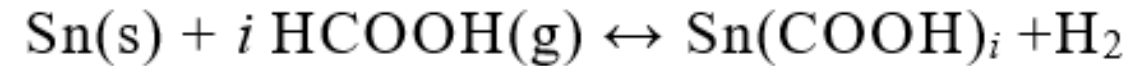
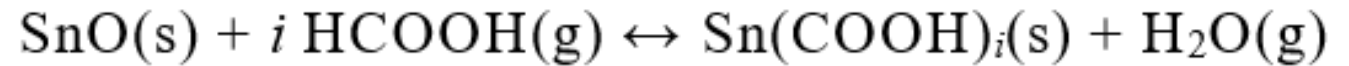
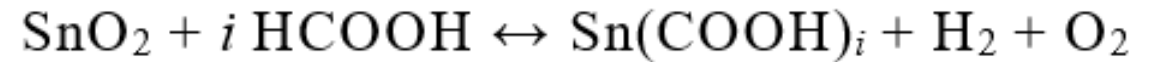


# Metal Formiate Desorption



*Transportation process by formiate desorption*

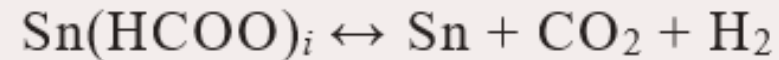
## ■ Adsorption around 150°C - 190°C



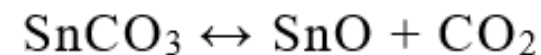
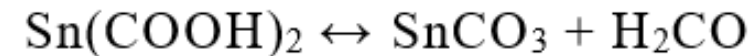
## ■ Desorption around 200°C - 215°C



## ■ Decomposition around 200°C - 215°C



## ■ Carbonate formation



# Contamination



- Metall deposition can be observed around SAC powder on copper for formic acid driven solder process



Solder Paste with standar resin containing flux



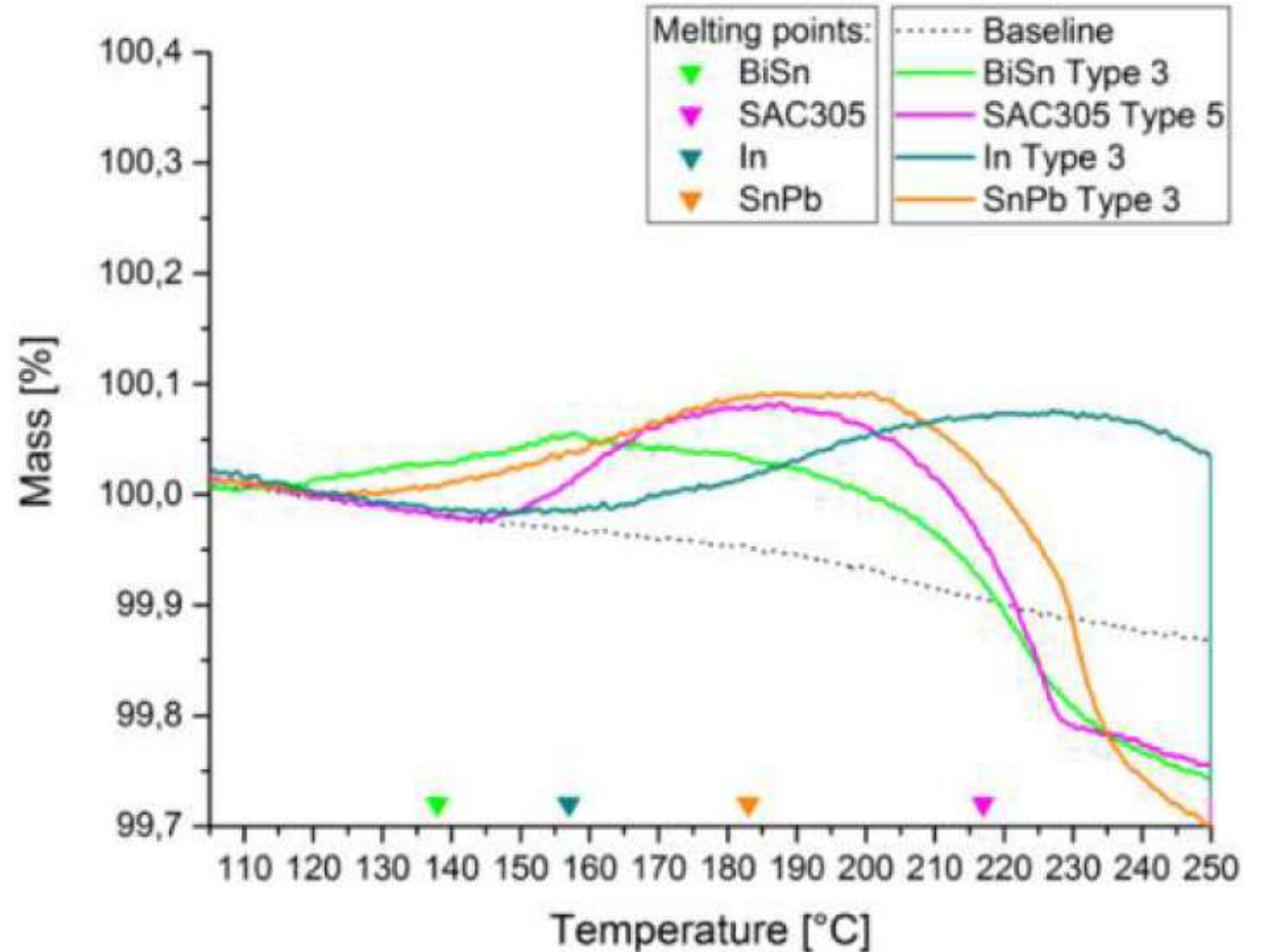
Pure organic carrier

# Formiate Formation and Desorption



SAC305 – BiSn – In - SnPb

- Formiate formation and desorption / decomposition depends on metal

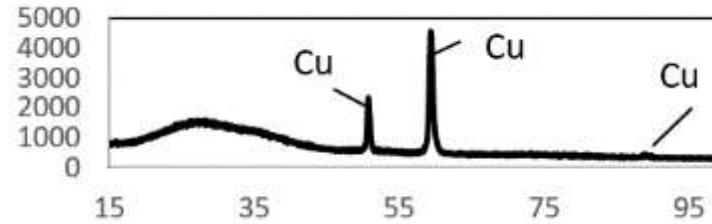
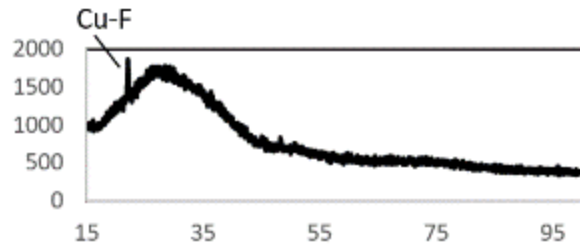


# Metal Formiate Evaporation



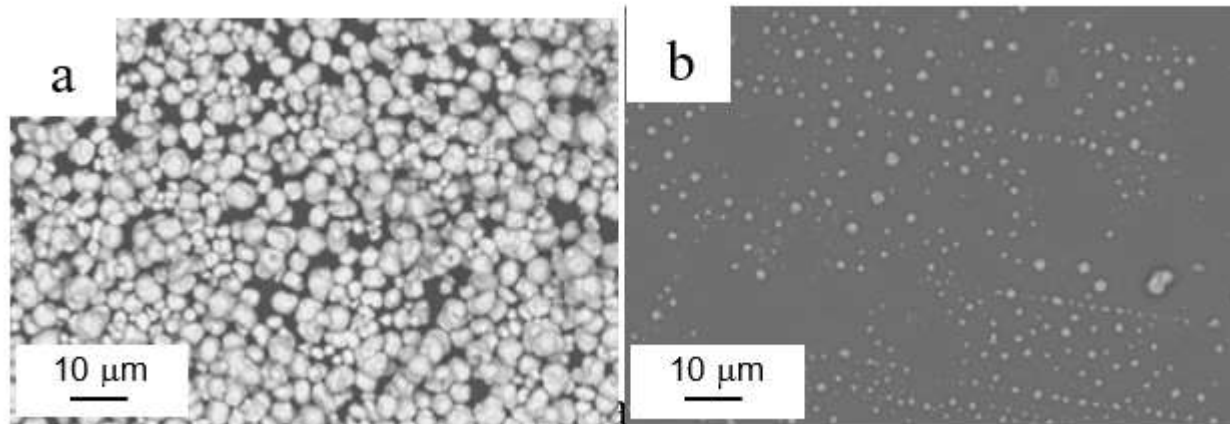
*Crystal formation on top plate using Copper*

## ■ Crystal's grow on the top surface (Copper)



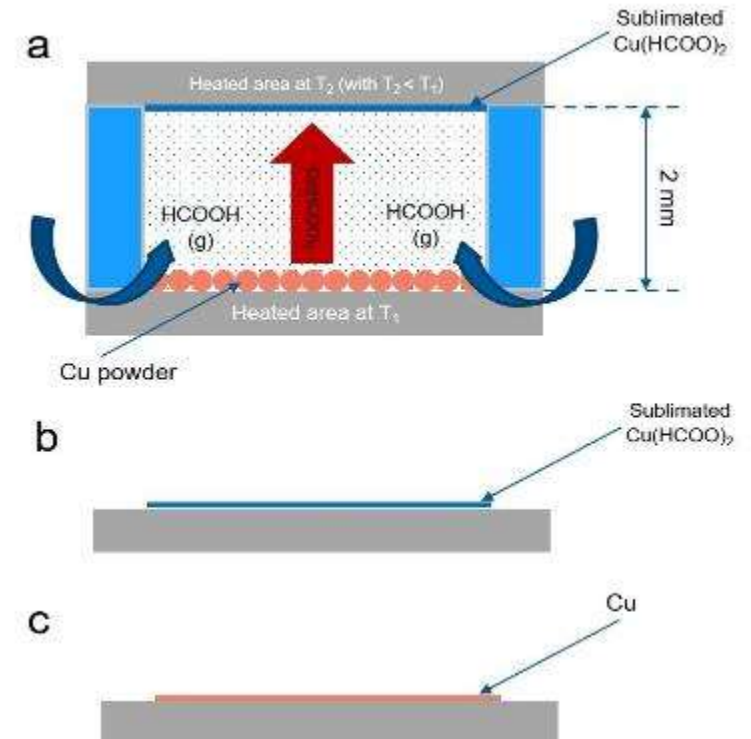
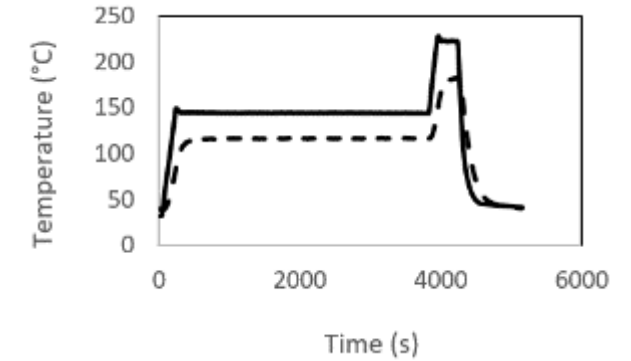
XRD: taken out before heating to 240°C

XRD: after 240°C



Copper powder bottom

Copper deposition top



# Chemical Vapor Deposition (CVD) of Copper



*CVD Based on gaseous copper formiate chemical vapor deposition of copper*

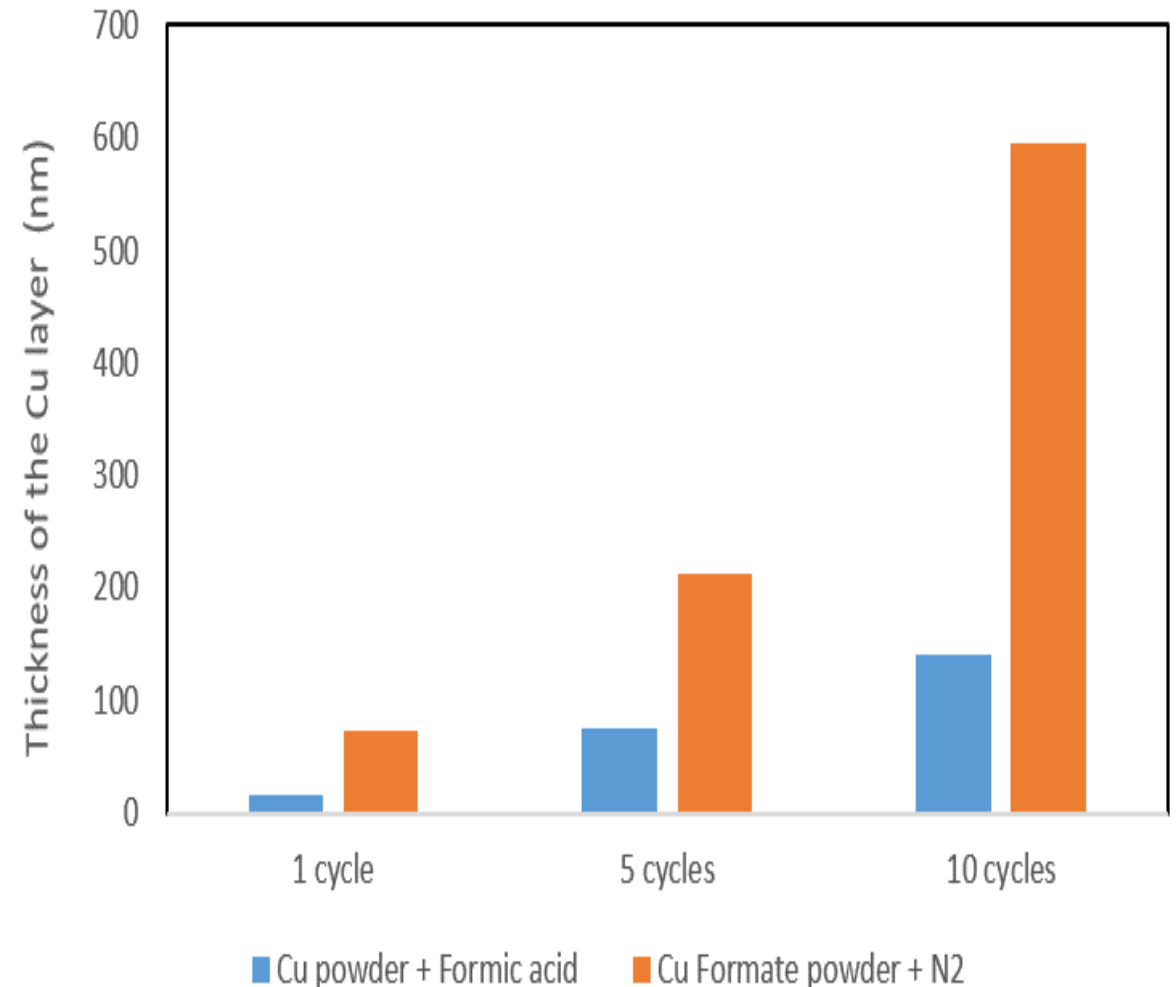
## ■ The CVD process for copper based on desorbed formiate is known

M. S. Polyakov, A. M. Badalyan, V. K. Vasiliy and I. K. Igumenov, Thermal- and Plasma-Enhanced Copper Film Deposition via a Combined Synthesis-Transport CVD Technique, Chem. Vap. Deposition 2014, 20, 170–176.

- Argon gas is At 120°C – 140°C / 10mbar argon gas enriched with formic acid is conducted via copper
- Gas is afterwards conducted over a 220°C-300°C hot surface
- Copper is deposited on the surface

## ■ Experiment in reflow oven at atmospheric pressure:

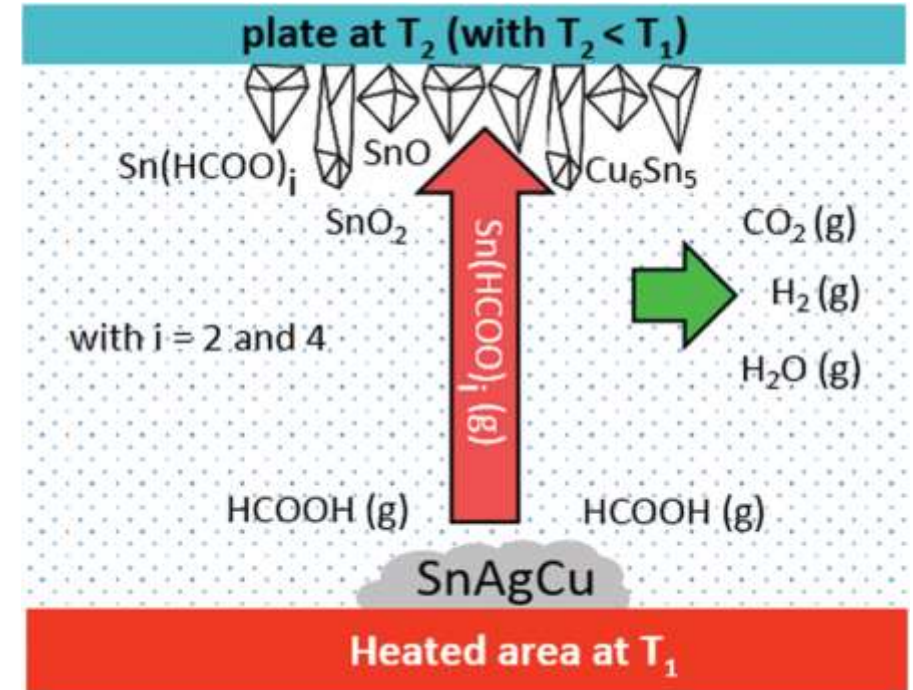
- Nitrogen enriched with formic acid
- Evaporation at 150°C
- Decomposition at 240°C
- Copper powder and copper formiate powder



# Conclusion



- Desorption of metal formiate is observed
- Metal formite decomposes also in the same temperature range
- Risk of metal, metal oxide and carbonate contamination due to decomposition of gaseous metal formiate
- To enable clean process
  - Binder of flux reduces outgasing of metal formiate
  - Process parameter adjustment (pressure, temperature formic acid concentration)



# Introduction

*AuSn Solder Process under Formic Acid*





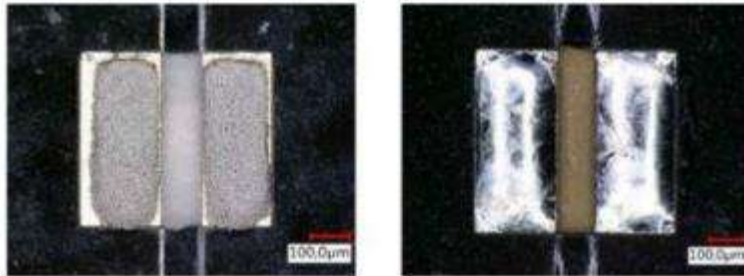


# Fluxfree Soldering with SAC paste



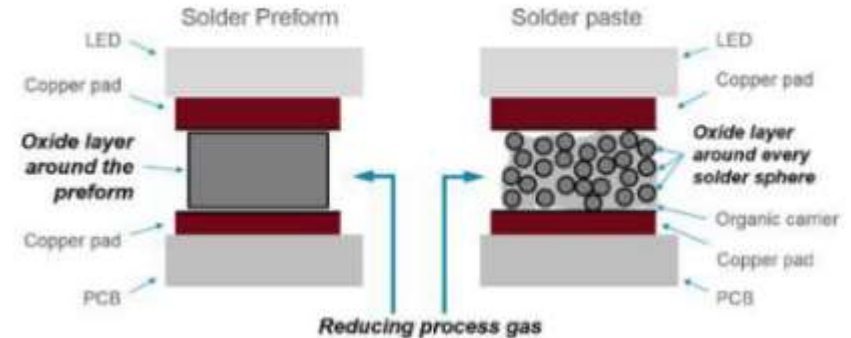
- SAC305 Type 5 solder powder in flux-free carrier medium
- Solder paste printing
- Reflow under formic acid

**Figure 12** Pictures of a fluxless SAC305 solder paste after reflow without reducing atmosphere (left picture) and with gaseous activator (right picture) (magnification: 60x)

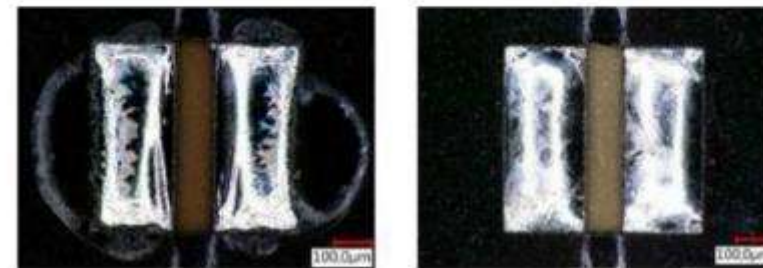


Residual free solder process for fluxless solder pastes, 217, Soldering & Surface Mount Technolog, <https://doi.org/10.1108/SSMT-10-2017-0030>

**Figure 2** The principle of fluxless soldering with a preform (left picture) and fluxless solder paste (right picture)



**Figure 6** Optical inspection of the solder joint soldered with conventional flux solder paste (left picture) and a sample soldered with fluxless solder paste (right picture) (magnification: 60x)



# Thermo Gravimetric Analysis



- Investigation of different solder and copper powder under formic acid enriched nitrogen

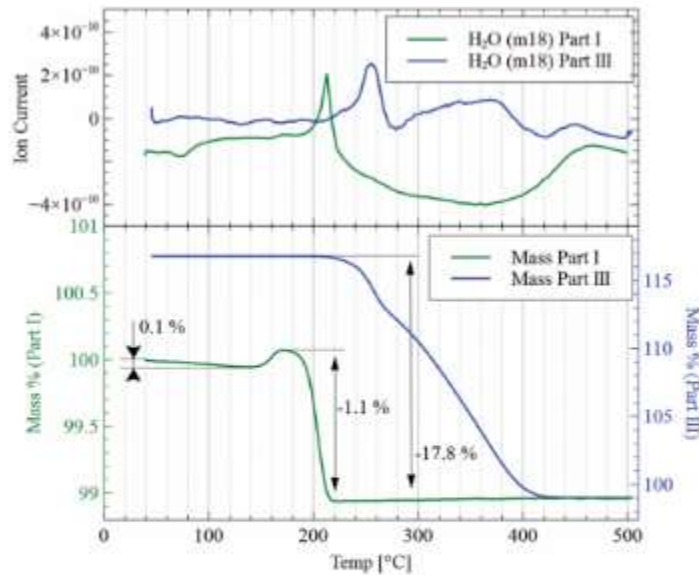
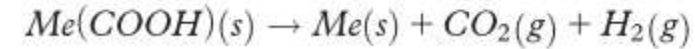
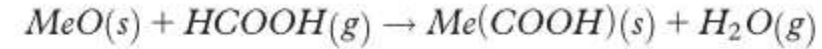
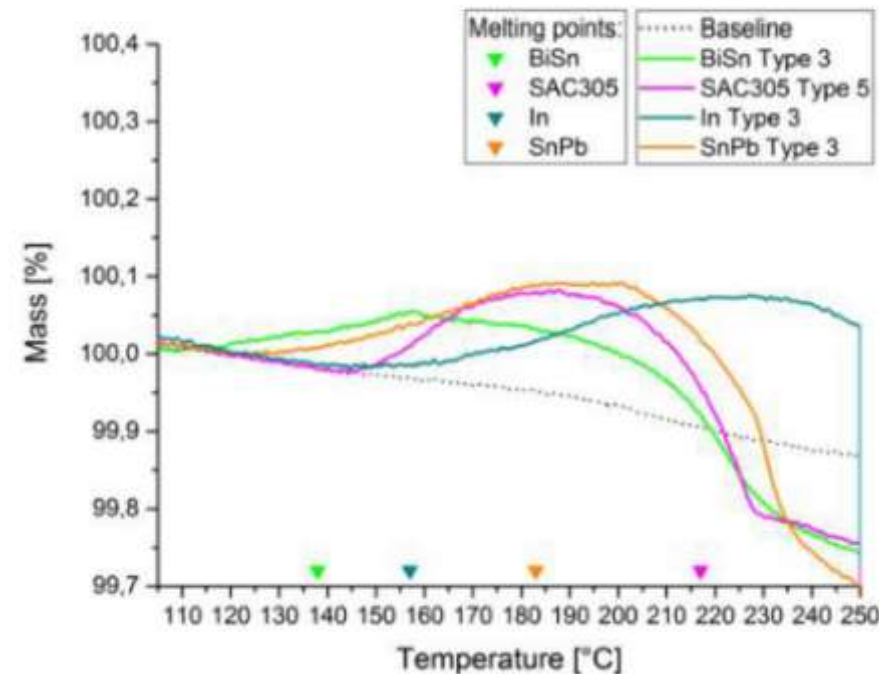


Fig. 5 Comparison of the results obtained using formic acid on the pristine copper powder (green lines, process in region I) and on the fully oxidised copper powder (blue lines, process in region III). Top: Mass signals of water. Bottom: TGA profiles (the signal of mass part I is magnified by a factor 9).

Fosca Conti, Alexander Hanss, Carolin Fischer, Gordon Elger, Thermogravimetric investigation on the interaction of formic acid with solder joint Materials, New Journal of Chemistry, 201640, 10482--10487

Figure 10 Results of the TGA and the melting points of different solder alloys





■ **Thanks for your attention**

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